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(19) **United States**(12) **Patent Application Publication**
MORIMOTO(10) **Pub. No.: US 2018/0263594 A1**(43) **Pub. Date: Sep. 20, 2018**(54) **SEMICONDUCTOR DEVICE, ULTRASONIC
IMAGE PICKUP DEVICE,
SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, AND
ULTRASONIC IMAGING SYSTEM***H01L 27/088* (2006.01)*H01L 27/12* (2006.01)*H01L 29/786* (2006.01)*H01L 29/868* (2006.01)(52) **U.S. Cl.**CPC *A61B 8/14* (2013.01); *H01L 21/762*(2013.01); *H01L 21/8234* (2013.01); *H01L**29/868* (2013.01); *H01L 27/088* (2013.01);*H01L 27/12* (2013.01); *H01L 29/786*(2013.01); *H01L 27/06* (2013.01)(71) Applicant: **SONY CORPORATION, TOKYO (JP)**(72) Inventor: **RUI MORIMOTO, KANAGAWA (JP)**(21) Appl. No.: **15/760,068**(22) PCT Filed: **Jul. 15, 2016**(86) PCT No.: **PCT/JP2016/003366**

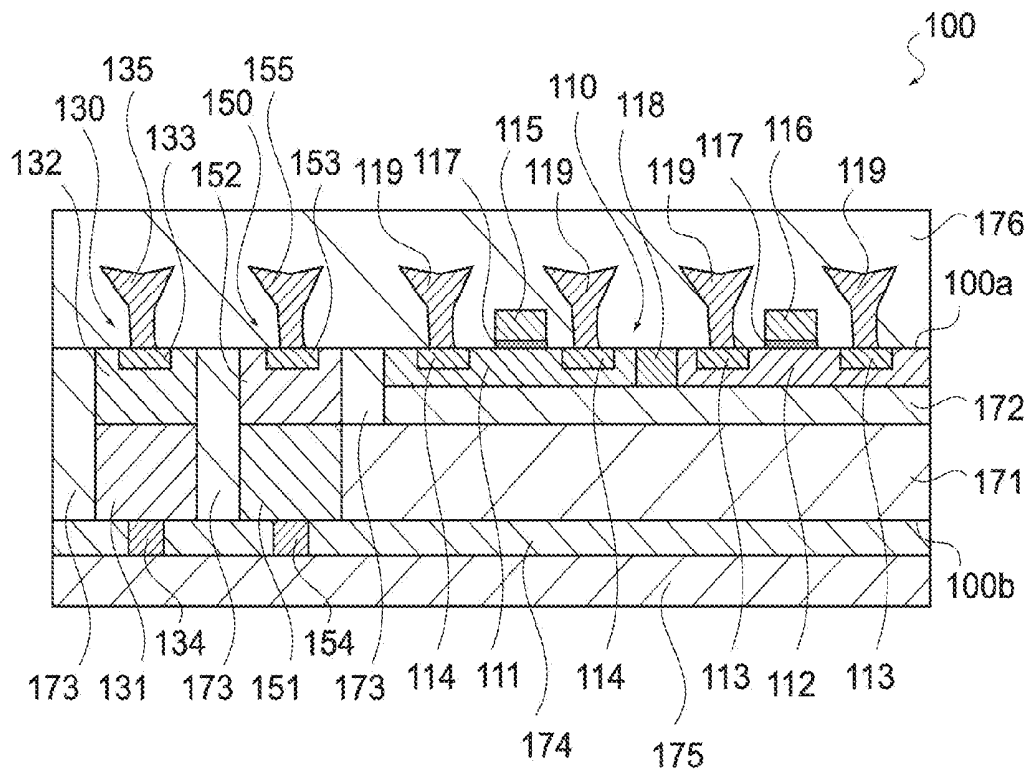
§ 371 (c)(1),

(2) Date: **Mar. 14, 2018**(30) **Foreign Application Priority Data**

Sep. 29, 2015 (JP) 2015-190920

Publication Classification(51) **Int. Cl.***A61B 8/14* (2006.01)*H01L 21/762* (2006.01)*H01L 21/8234* (2006.01)*H01L 27/06* (2006.01)**ABSTRACT**

[Object] To provide a semiconductor device including a protection circuit that exhibits satisfactory performance even in a small area, an ultrasonic image pickup device, a semiconductor device manufacturing method, and an ultrasonic imaging system. [Solving Means] The semiconductor device according to the present technology includes an integrated circuit formed on an SOI substrate including a silicon substrate formed of crystalline silicon, a BOX layer laminated on the silicon substrate, and an SOI layer laminated on the BOX layer, the semiconductor device including: a protection circuit; and an element separation region. The protection circuit constitutes the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate. The element separation region penetrates the SOI substrate and separates the protection circuit.



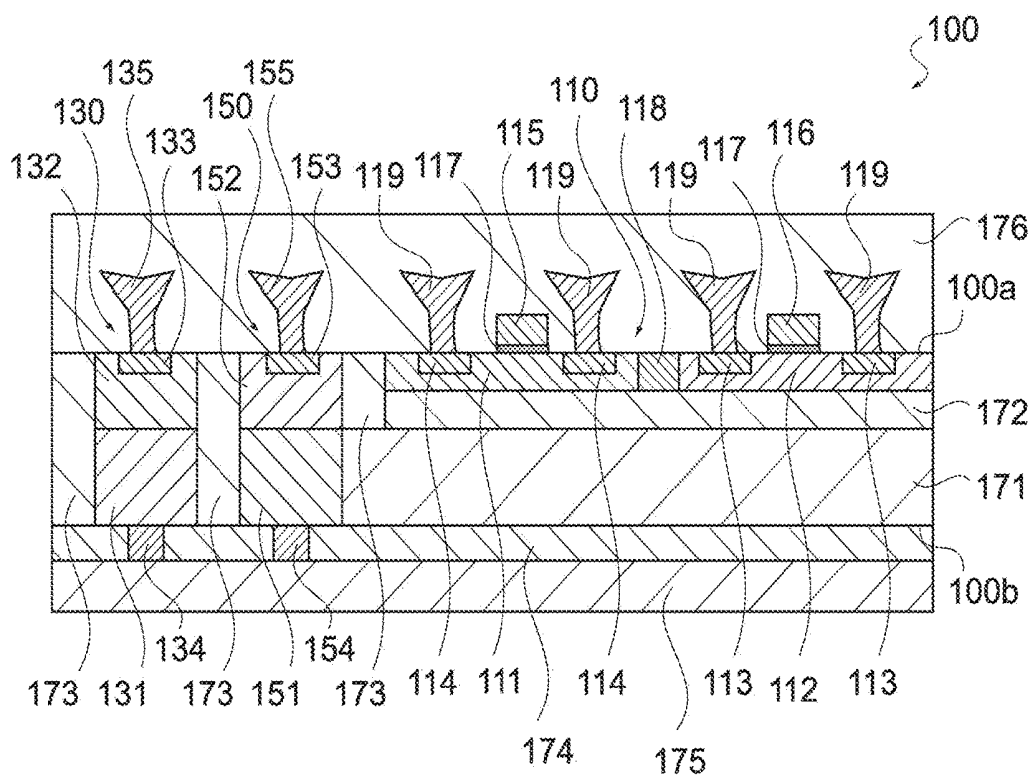


FIG.1

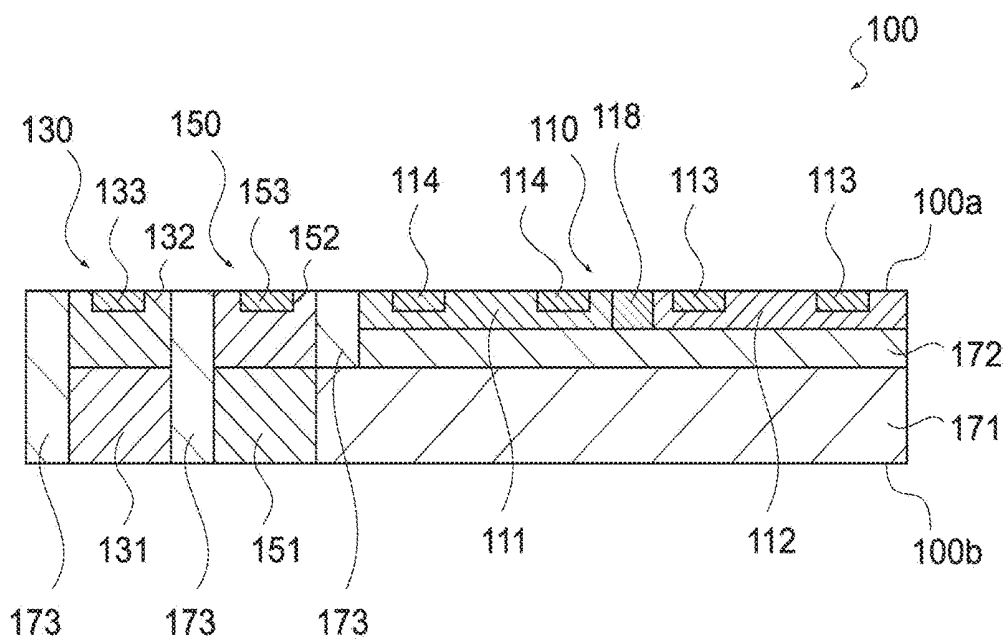


FIG.2

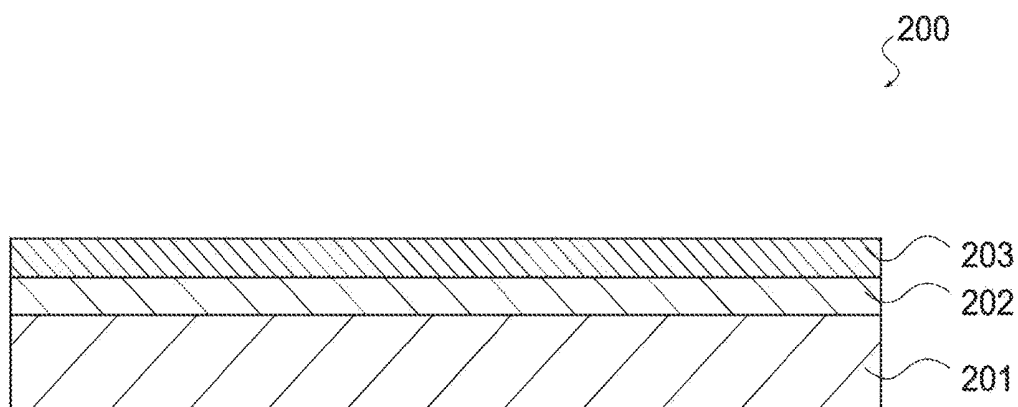


FIG.3

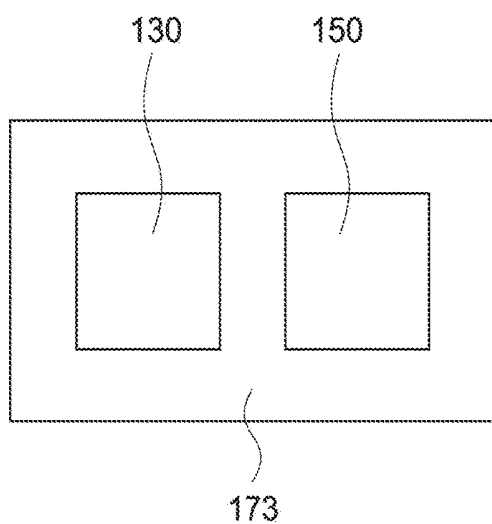


FIG.4

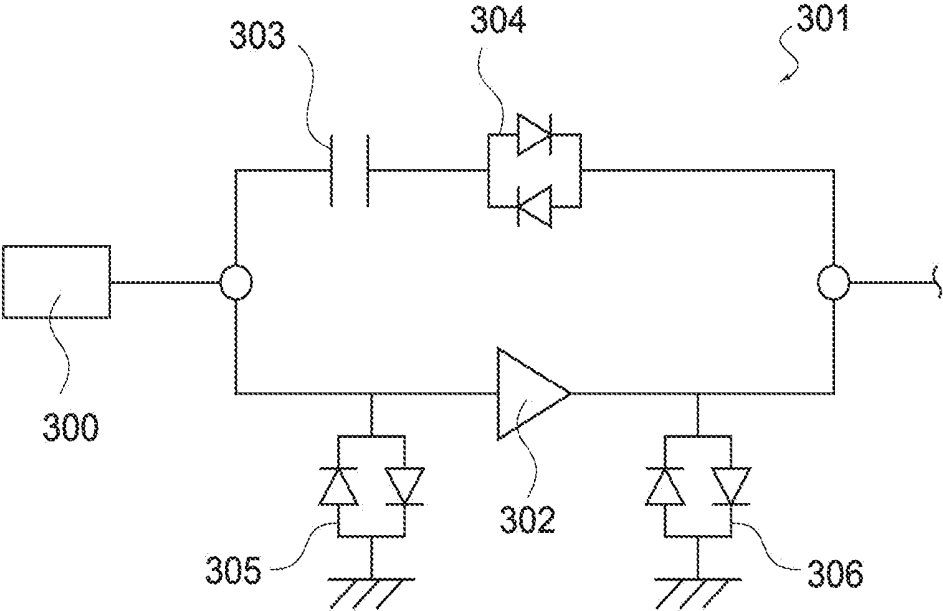


FIG.5

FIG. 6(a)

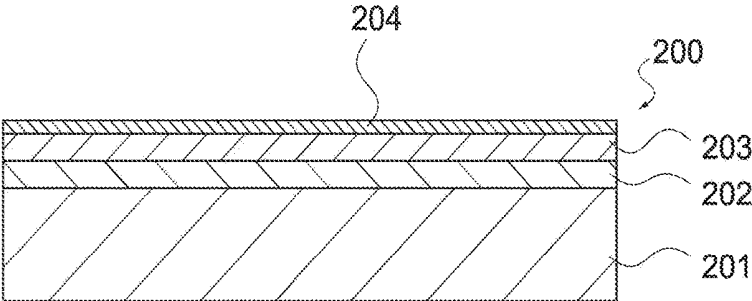


FIG. 6(b)

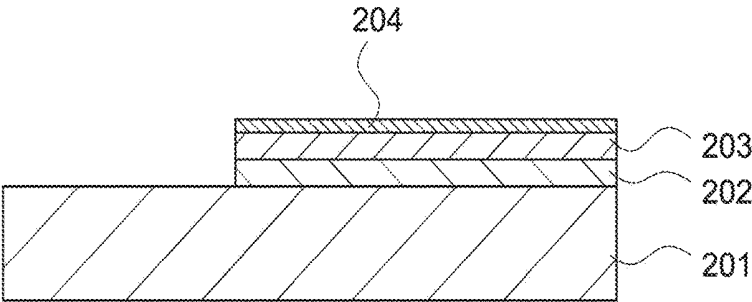
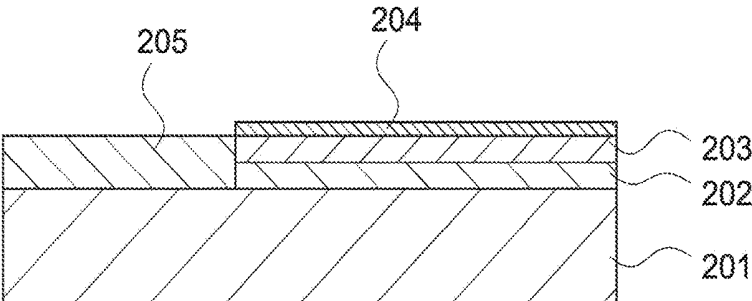


FIG. 6(c)



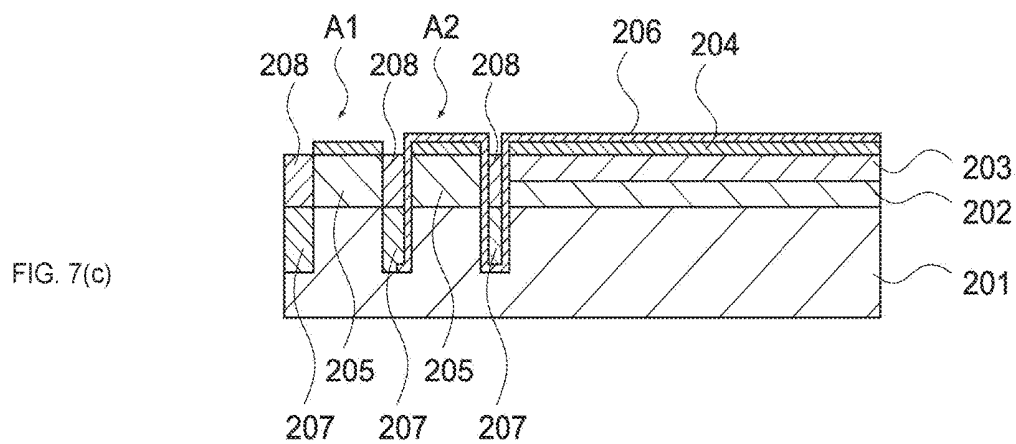
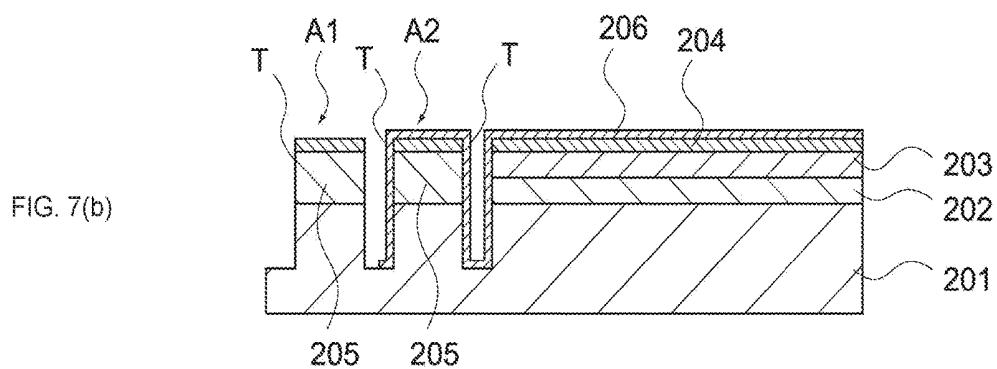
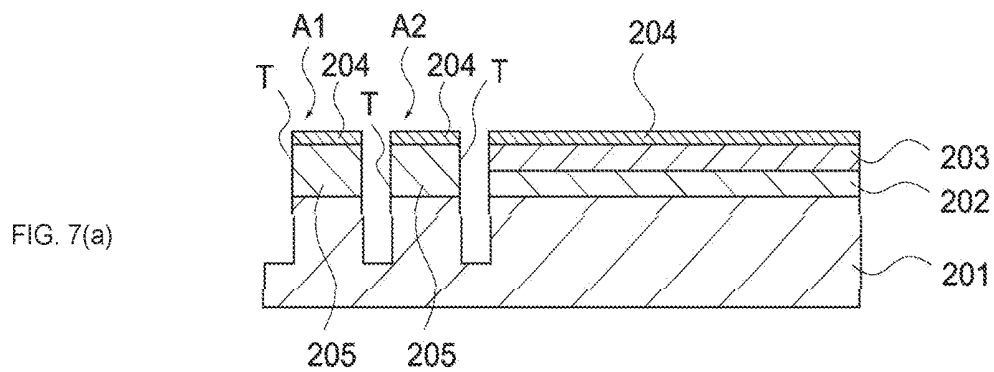


FIG. 8(a)

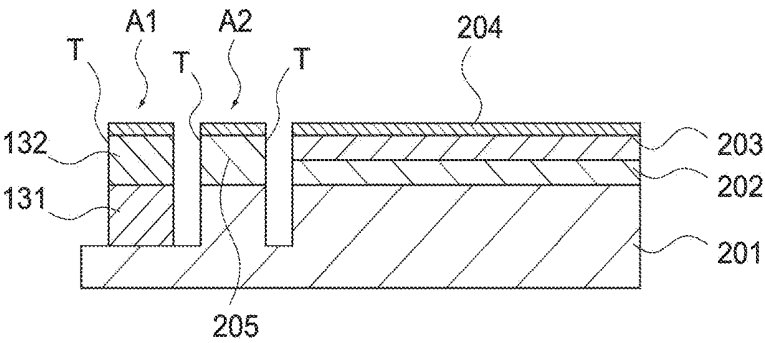


FIG. 8(b)

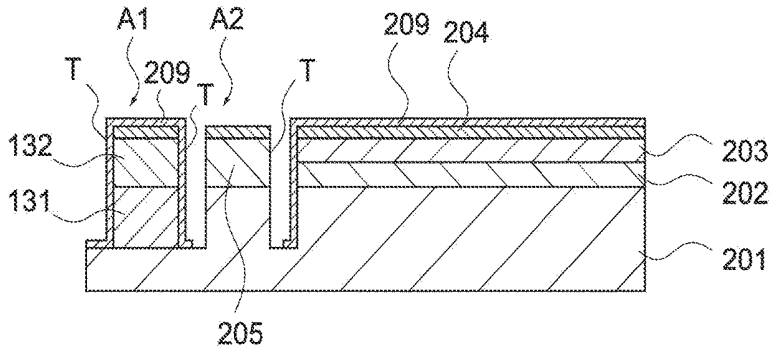
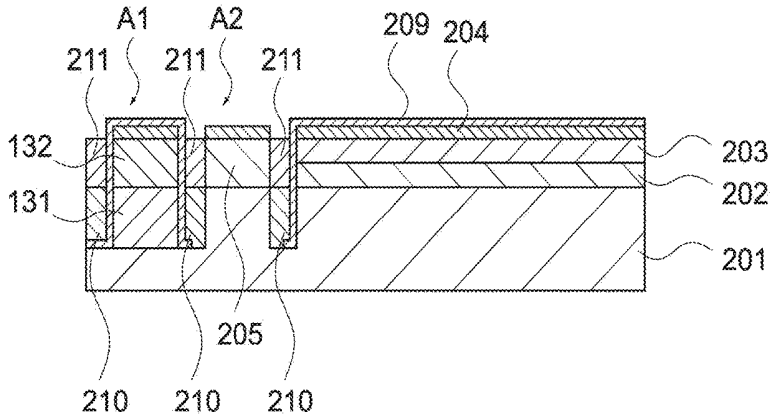
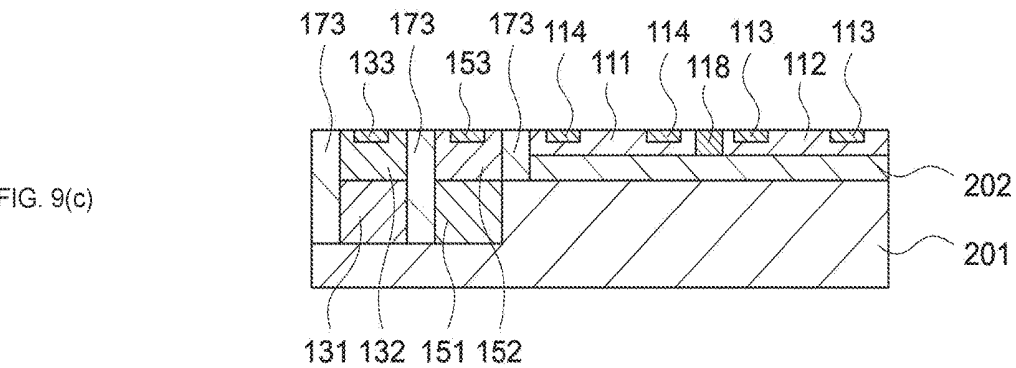
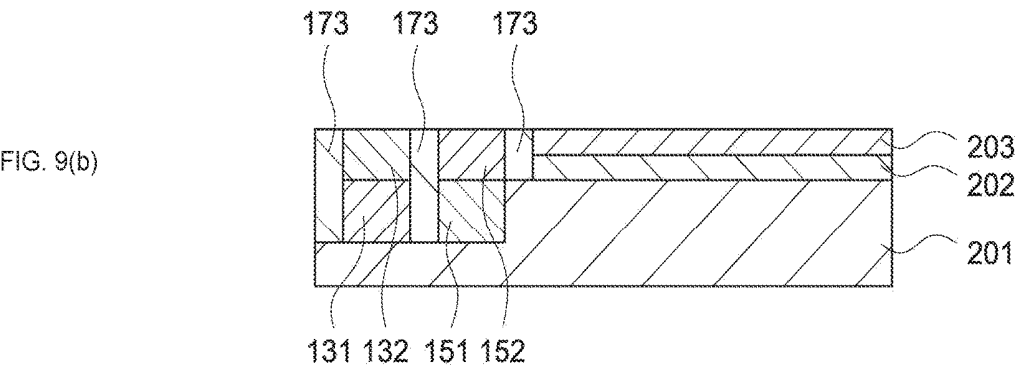
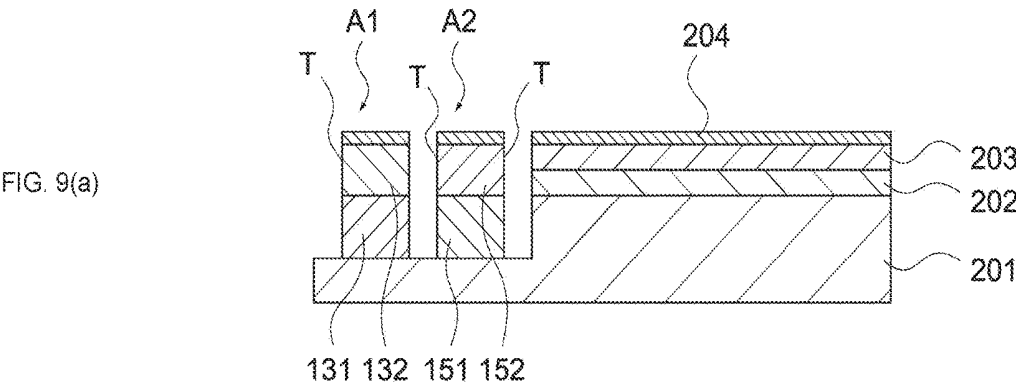
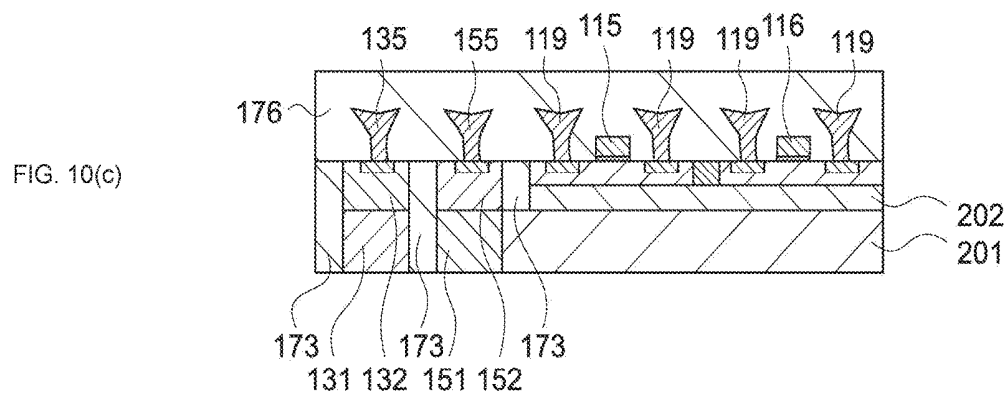
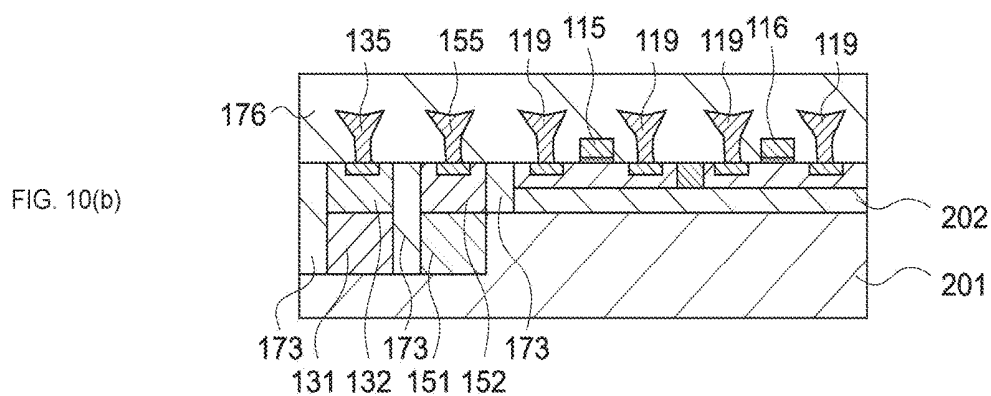
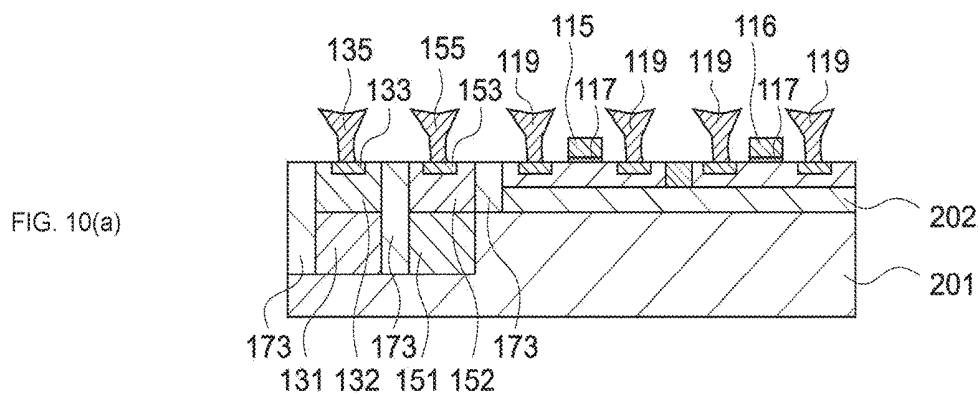
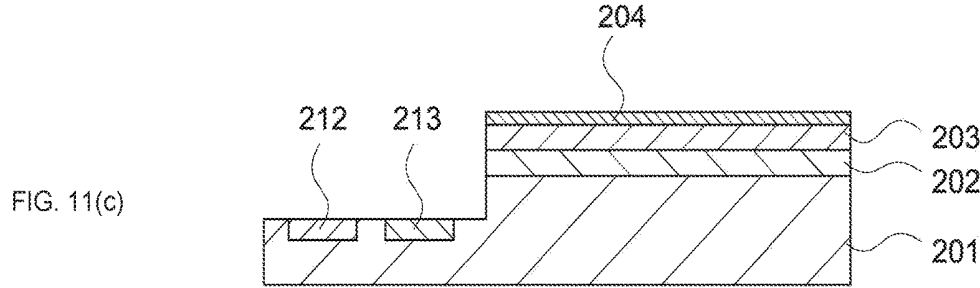
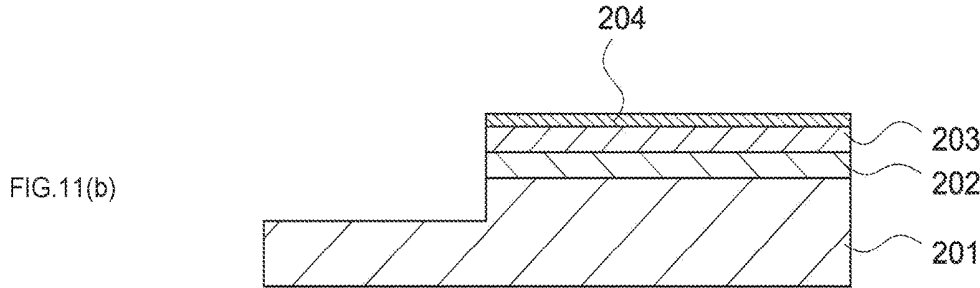
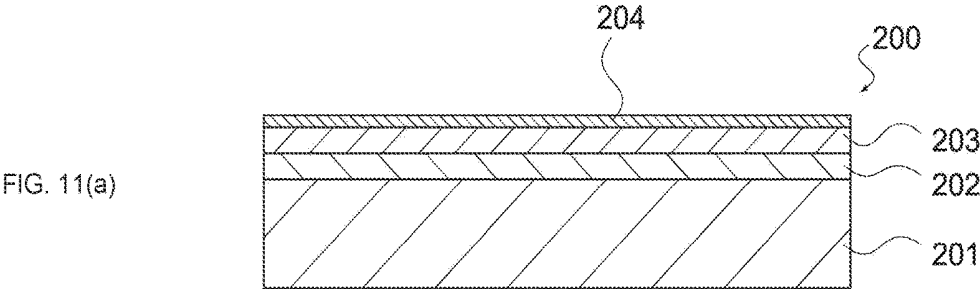


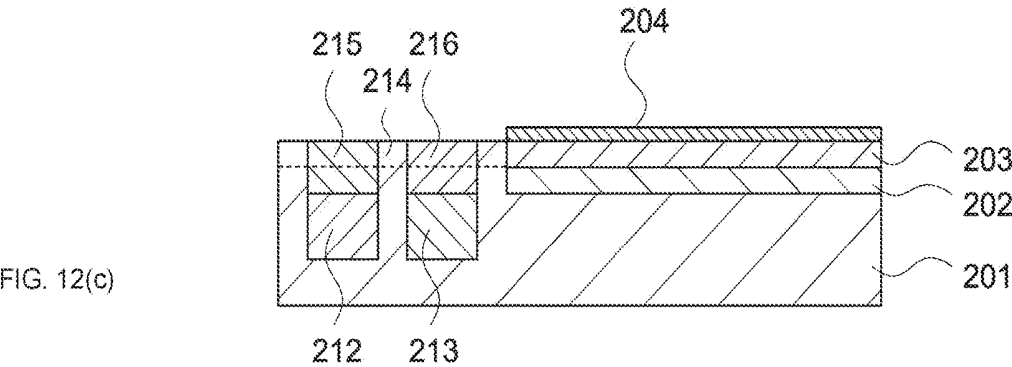
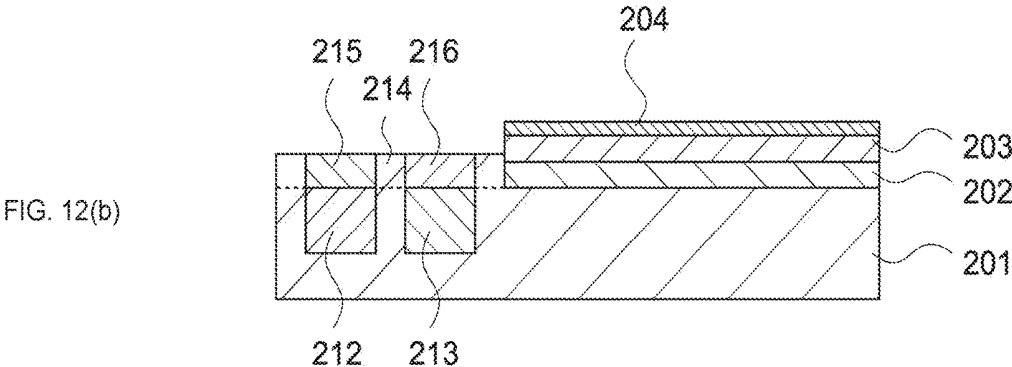
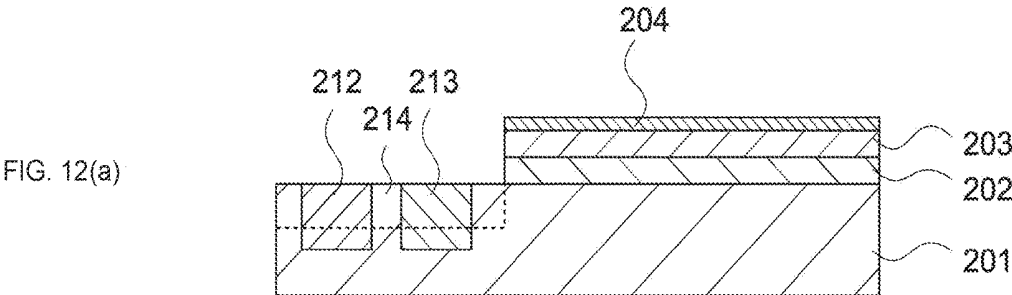
FIG. 8(c)

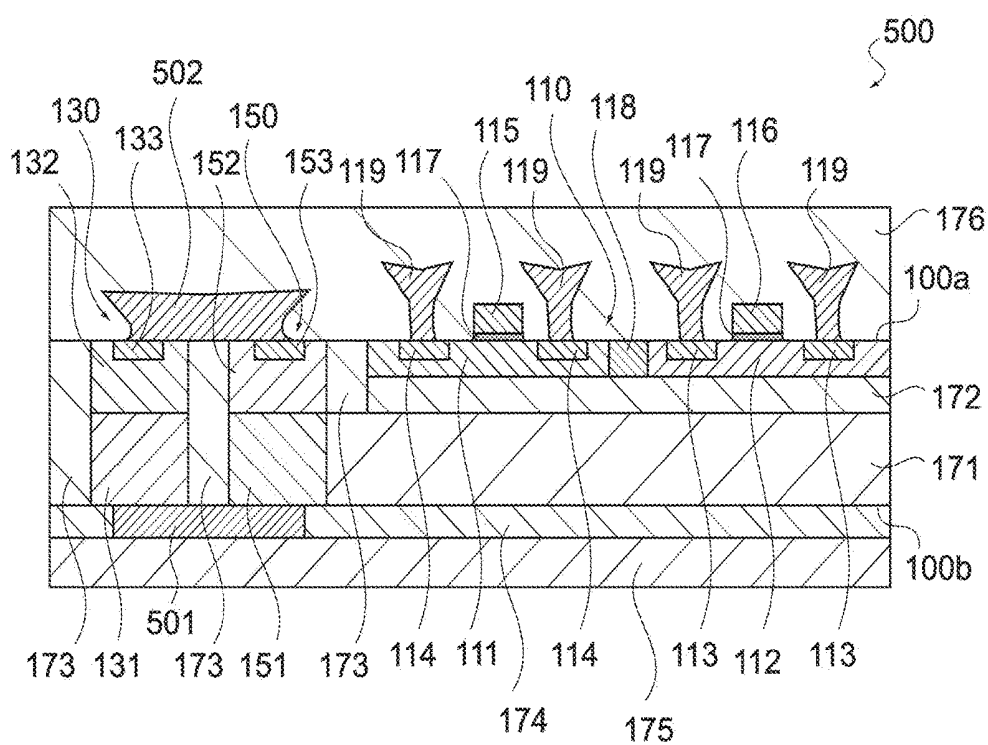
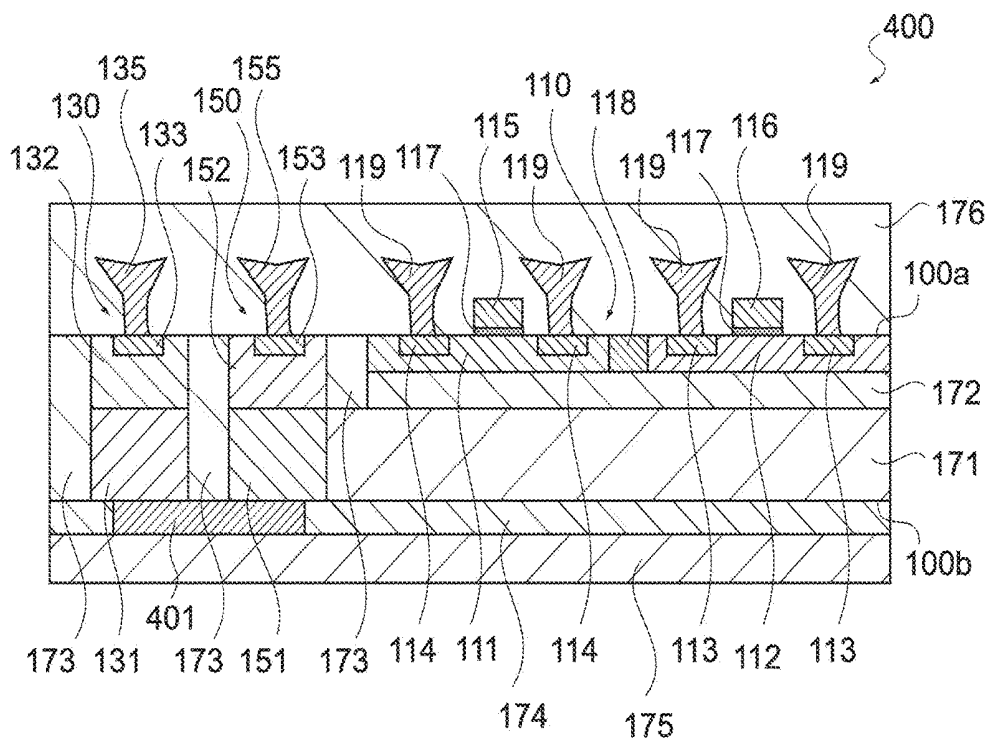












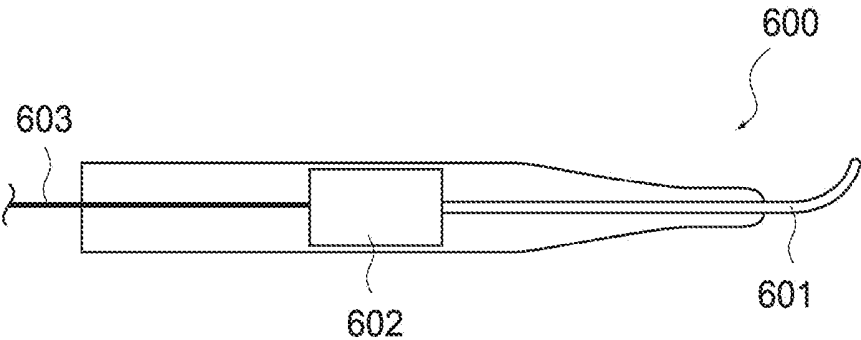


FIG.15

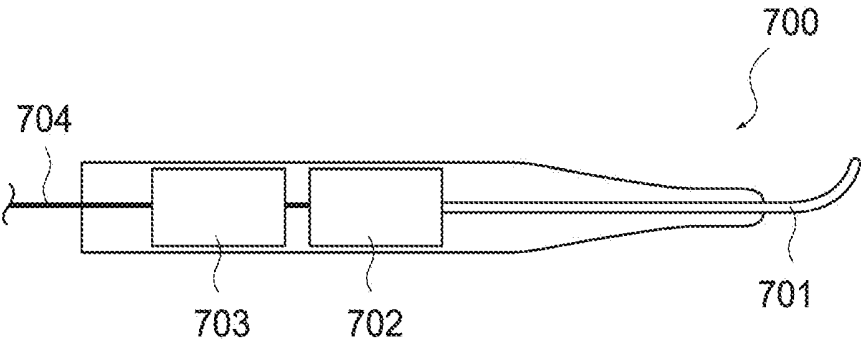


FIG.16

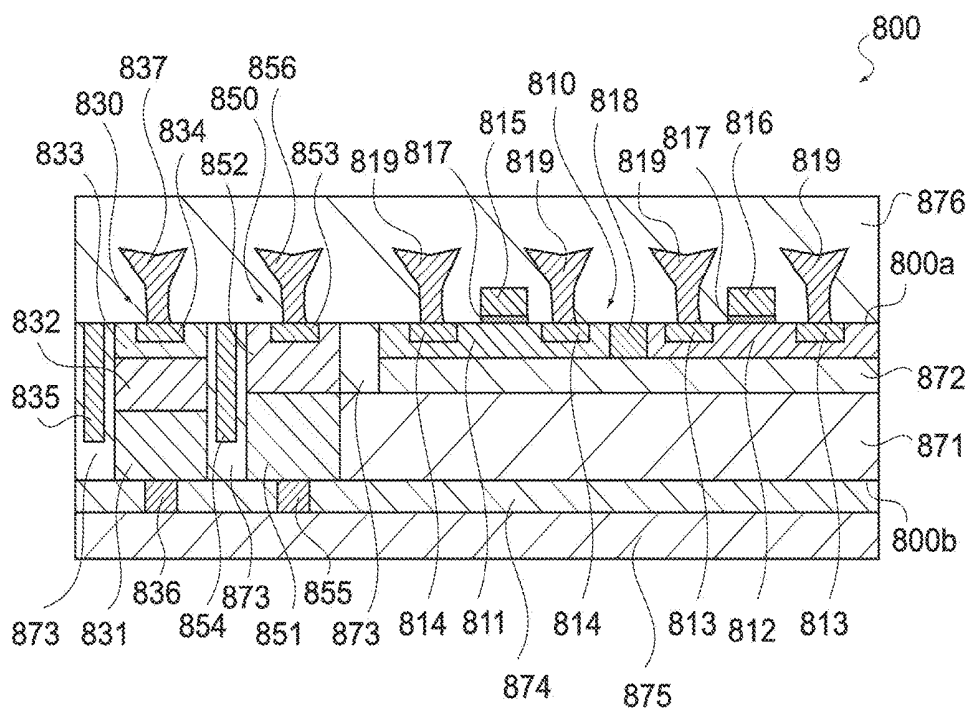


FIG. 17

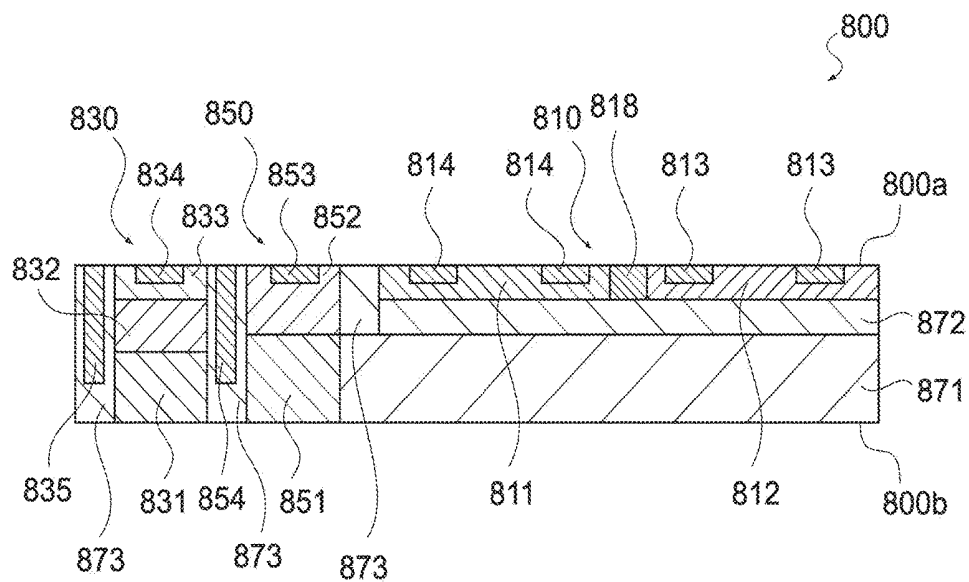


FIG. 18

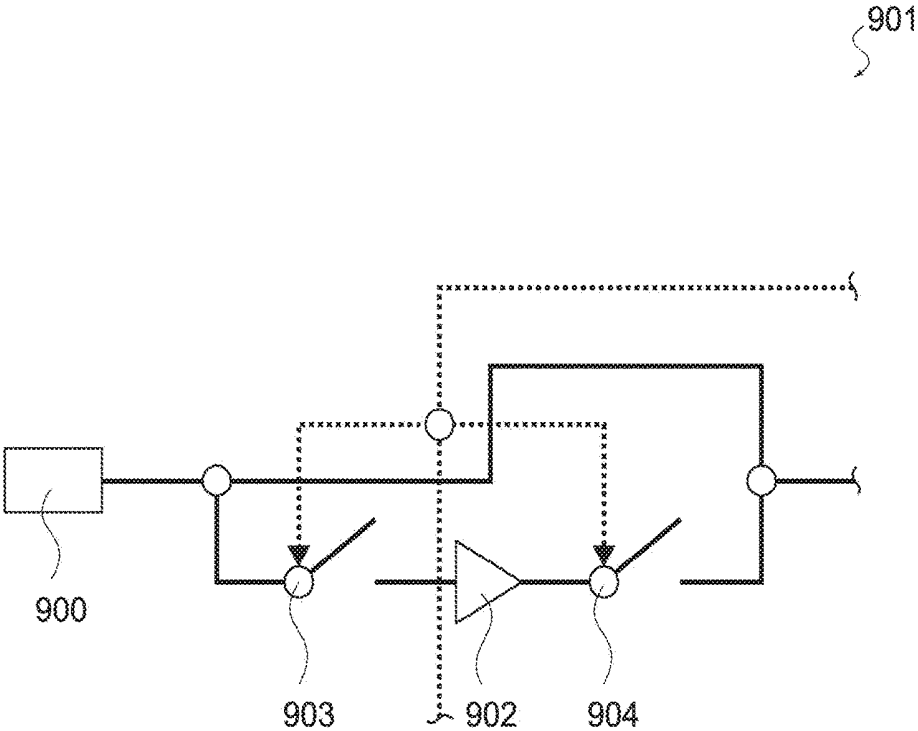


FIG.19

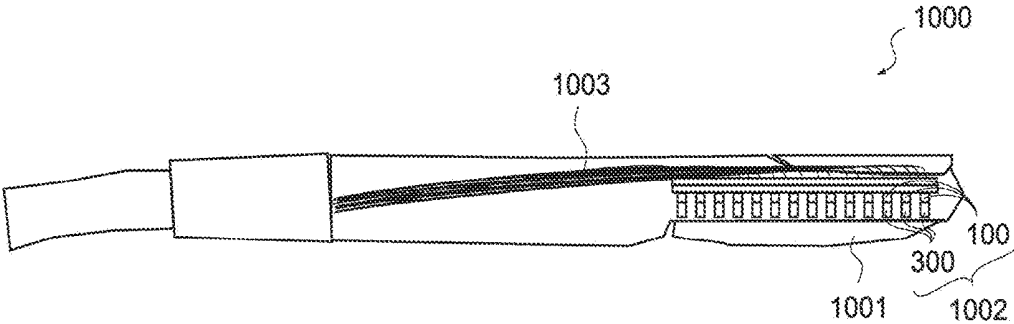


FIG.20

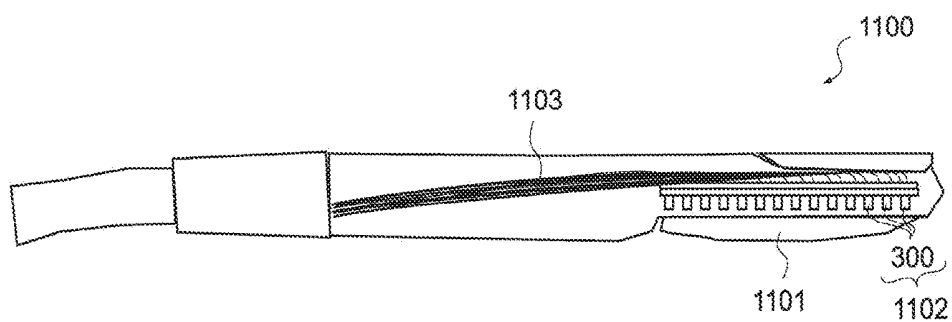


FIG. 21

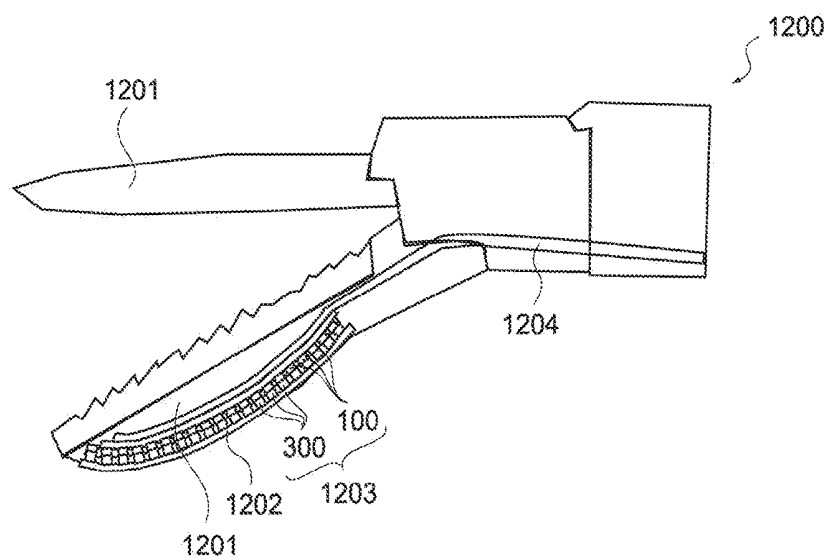


FIG. 22

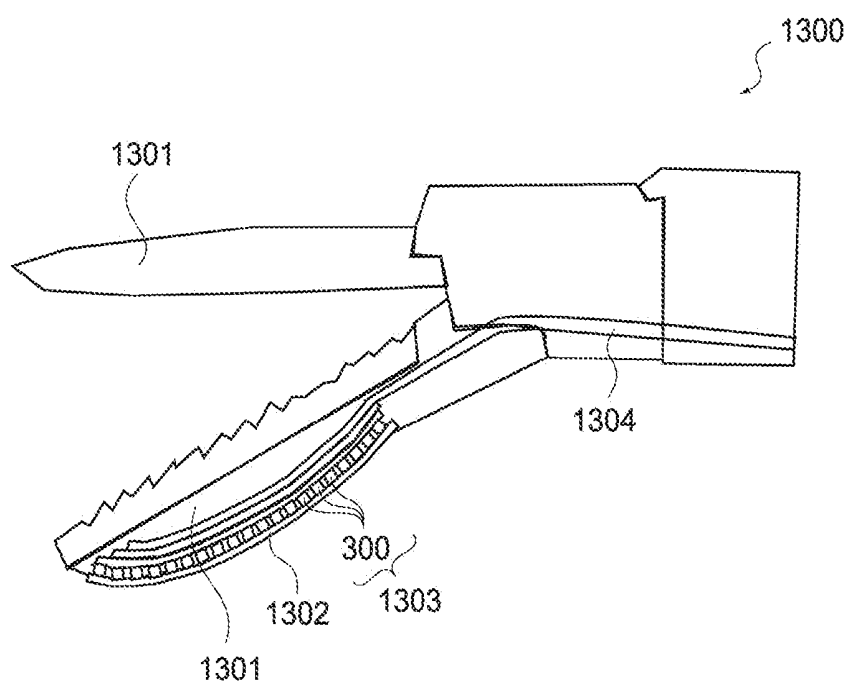


FIG.23

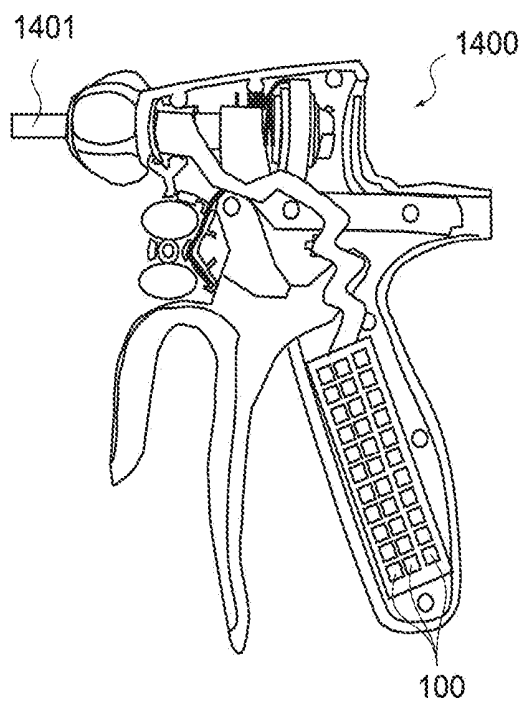


FIG.24

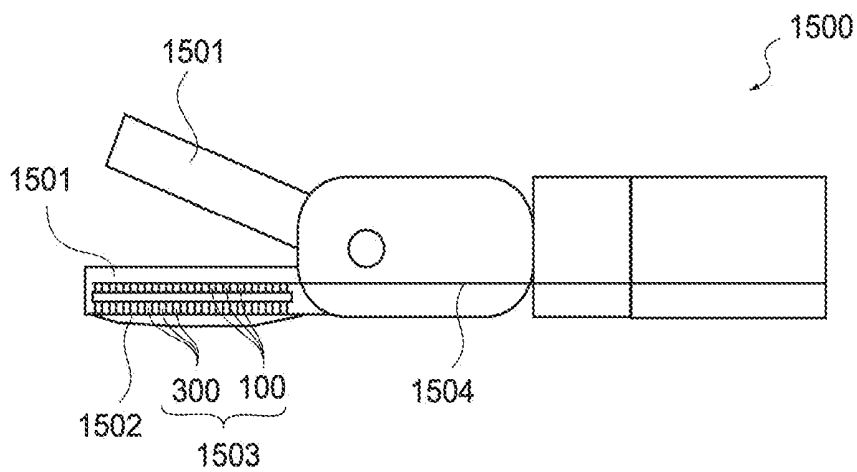


FIG.25

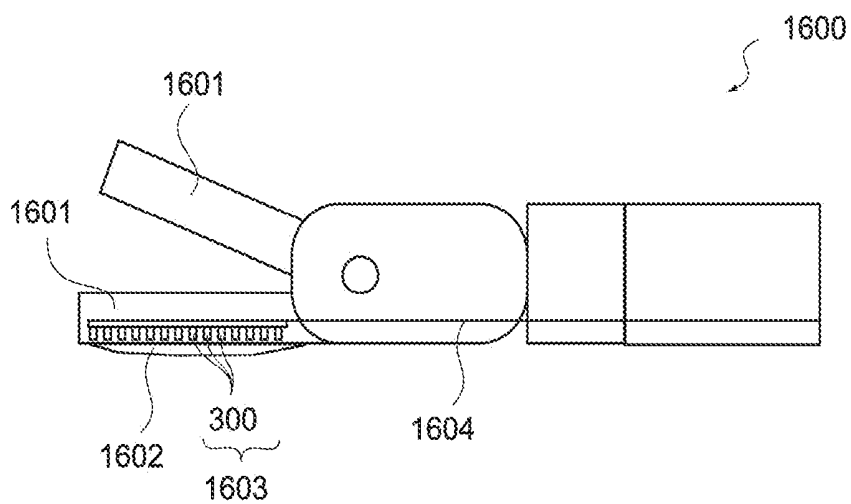


FIG.26

**SEMICONDUCTOR DEVICE, ULTRASONIC
IMAGE PICKUP DEVICE,
SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, AND
ULTRASONIC IMAGING SYSTEM**

TECHNICAL FIELD

[0001] The present technology relates to a semiconductor device including an integrated circuit including protection circuits, an ultrasonic image pickup device, a semiconductor device manufacturing method, and an ultrasonic imaging system.

BACKGROUND ART

[0002] Ultrasonic imaging refers to generation of ultrasonic images by applying ultrasonic waves from an ultrasonic transducer to a measurement target, and detecting reflected waves generated from the measurement target with the ultrasonic transducer. The ultrasonic imaging has been utilized in ultrasonic endoscopes and ultrasonic catheters.

[0003] In this context, there is a significant difference between drive voltage to be applied to the ultrasonic transducer such that the ultrasonic waves are generated, and signal voltage to be generated by the ultrasonic transducer through the detection of the ultrasonic waves. For example, the drive voltage is at most approximately several hundred V, and the signal voltage is at approximately several μ V.

[0004] In view of such circumstances, an amplifier circuit for amplifying the signal voltage is utilized. Meanwhile, when the drive voltage is applied to the amplifier circuit, the amplifier circuit fails. As a countermeasure, protection circuits that prevent the drive voltage from reaching the amplifier circuit are also needed. When these circuits are implemented to a single semiconductor circuit, an implementation space can be saved.

[0005] In this context, an SOI (silicon on insulator) substrate, which is excellent in voltage resistance, is suited to use as the semiconductor substrate including both the amplifier circuit and the protection circuits. For example, Patent Literature 1 discloses a semiconductor device obtained by implementing the amplifier circuit and the protection circuits to the single SOI substrate. In this semiconductor device, the amplifier circuit is formed on the SOI substrate, and the protection circuits are formed in through-holes formed in the SOI substrate. The protection circuits are made of polysilicon filled in the through-holes.

CITATION LIST

Patent Literature

[0006] Patent Literature 1: Japanese Patent Application Laid-open No. 2010-50156

DISCLOSURE OF INVENTION

Technical Problem

[0007] However, there is a disadvantage that polysilicon generally has high resistance, and hence diodes having satisfactory leakage-current characteristics are difficult to form owing to defects in polysilicon. Further, the SOI substrate generally has a thickness of approximately 0.8 mm, and a manufacturing process of forming the through-holes each having a width of several ten μ m in such an SOI

substrate is difficult to execute. When the widths of the through-holes are increased to relax an aspect ratio (opening/depth), areas of elements are difficult to reduce.

[0008] In view of such circumstances, the present technology has been made to achieve an object to provide a semiconductor device including a protection circuit that exhibits satisfactory performance even in a small area, an ultrasonic image pickup device, a semiconductor device manufacturing method, and an ultrasonic imaging system.

Solution to Problem

[0009] In order to achieve the above-mentioned object, according to an embodiment of the present technology, there is provided a semiconductor device including an integrated circuit formed on an SOI substrate including

[0010] a silicon substrate formed of crystalline silicon,

[0011] a BOX (buried oxide) layer laminated on the silicon substrate, and

[0012] an SOI (silicon on insulator) layer laminated on the BOX layer, the semiconductor device including:

[0013] a protection circuit; and

[0014] an element separation region.

[0015] The protection circuit constitutes the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate.

[0016] The element separation region penetrates the SOI substrate and separates the protection circuit.

[0017] With this configuration, a semiconductor device in which an integrated circuit including a protection circuit is formed on a single SOI substrate can be provided. The semiconductor region of this protection circuit is made of the crystalline silicon having the same crystal orientation as the silicon substrate. The crystalline silicon is higher in movability than amorphous silicon such as polysilicon. Thus, it is possible to reduce areas of elements of the protection circuit, and to secure satisfactory leakage-current characteristics.

[0018] The protection circuit may be a diode.

[0019] This configuration enables the diode to serve as a TR (transmit-receive) switch, and the diode can be utilized as the protection circuit.

[0020] The protection circuit may be a vertical transistor.

[0021] This configuration enables the vertical transistor to serve as the TR switch, and the vertical transistor can be utilized as the protection circuit.

[0022] The element separation region may be formed of any one or two or more of silicon oxide, silicon nitride, and polysilicon.

[0023] The element separation region can be formed by forming a silicon oxide film or a silicon nitride film in a through-hole formed in the SOI substrate, and by filling polysilicon therein.

[0024] The element separation region may include a gate electrode of the vertical transistor.

[0025] By connecting wires to the polysilicon filled in the element separation region, this polysilicon can be utilized as the gate electrode of the vertical transistor.

[0026] The SOI substrate may include a first surface and a second surface on a side opposite to the first surface,

[0027] the protection circuit may include a first semiconductor element and a second semiconductor element,

- [0028] the first semiconductor element may be formed by laminating a first semiconductor region that is on the first surface side and is of a first impurity type, and a second semiconductor region that is on the second surface side and is of a second impurity type, and
- [0029] the second semiconductor element may be formed by laminating a third semiconductor region that is on the first surface side and is of the second impurity type, and a fourth semiconductor region that is on the second surface side and is of the first impurity type.
- [0030] This configuration enables the first semiconductor element and the second semiconductor element to serve as a back-to-back diode. The back-to-back diode refers to a pair of diodes configured in a manner that a P-type semiconductor region of one is connected to an N-type semiconductor region of another. In a large number of high-voltage elements, this back-to-back diode is used as an element having a function of a Zener diode.
- [0031] The above-described semiconductor device may further include
- [0032] a ground contact structure that is provided on the first surface of the semiconductor device and is electrically conducted to the first semiconductor region and the third semiconductor region.
- [0033] With this, wire routing to the back-to-back diode is simplified. As a result, improvement in yield, reduction in manufacturing cost, and enhancement in wiring reliability can be achieved.
- [0034] The ground contact structure may include a ground wire that is connected to the first semiconductor region and the third semiconductor region, and is common to both the first semiconductor region and the third semiconductor region.
- [0035] Potentials of adjacent ones of the semiconductor regions (first semiconductor region and third semiconductor region) of the back-to-back diode are equal to each other. Thus, both the regions can be connected to each other with the common ground wire.
- [0036] The ground contact structure may include a ground electrode that is connected to the ground wire, and is common to both the first semiconductor region and the third semiconductor region.
- [0037] This configuration enables the first semiconductor element and the second semiconductor element to be conducted to the common ground electrode.
- [0038] The above-described semiconductor device may further include
- [0039] a signal wire that is connected to the second semiconductor region and the fourth semiconductor region, and is common to both the second semiconductor region and the fourth semiconductor region.
- [0040] Potentials of other adjacent ones of the semiconductor regions (second semiconductor region and fourth semiconductor region) of the back-to-back diode are equal to each other. Thus, both the regions can be connected to each other with the common signal wire
- [0041] In order to achieve the above-mentioned object, according to another embodiment of the present technology, there is provided an ultrasonic image pickup device including
- [0042] a semiconductor device.
- [0043] This semiconductor device includes an integrated circuit formed on an SOI substrate including
- [0044] a silicon substrate formed of crystalline silicon,
- [0045] a BOX layer laminated on the silicon substrate, and
- [0046] an SOI layer laminated on the BOX layer, the semiconductor device including
- [0047] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
- [0048] an element separation region that penetrates the SOI substrate and separates the protection circuit.
- [0049] This semiconductor device can be utilized as an impedance matching circuit of an ultrasonic transducer of the ultrasonic image pickup device.
- [0050] According to still another embodiment of the present technology, there is provided a manufacturing method for a semiconductor device including an integrated circuit formed on an SOI substrate, the manufacturing method including:
- [0051] preparing the SOI substrate including
- [0052] a silicon substrate formed of crystalline silicon,
- [0053] a BOX layer laminated on the silicon substrate, and
- [0054] an SOI layer laminated on the BOX layer;
- [0055] forming, by an epitaxial crystal growth method, a protection circuit that configures the integrated circuit and includes a semiconductor region that has the same crystal orientation as the silicon substrate, on the silicon substrate; and
- [0056] forming an element separation region that penetrates the SOI substrate and separates the protection circuit.
- [0057] In the forming of the protection circuit, there may be used a substrate polishing method of polishing the silicon substrate from a surface on a side opposite to a surface on a side where crystal growth of the semiconductor region progresses, to expose the semiconductor region.
- [0058] According to yet another embodiment of the present technology, there is provided an ultrasonic imaging system including
- [0059] an ultrasonic catheter.
- [0060] This ultrasonic catheter includes a semiconductor device including an integrated circuit formed on an SOI substrate including
- [0061] a silicon substrate formed of crystalline silicon,
- [0062] a BOX layer laminated on the silicon substrate, and
- [0063] an SOI layer laminated on the BOX layer, the semiconductor device including
- [0064] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
- [0065] an element separation region that penetrates the SOI substrate and separates the protection circuit.
- [0066] According to yet another embodiment of the present technology, there is provided an ultrasonic imaging system including:
- [0067] an intraoperative ultrasonic probe; or
- [0068] an ultrasound endoscope.

[0069] This intraoperative ultrasonic probe or this ultrasound endoscope includes a semiconductor device including an integrated circuit formed on an SOI substrate including

[0070] a silicon substrate formed of crystalline silicon,

[0071] a BOX layer laminated on the silicon substrate, and

[0072] an SOI layer laminated on the BOX layer, the semiconductor device including

[0073] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and

[0074] an element separation region that penetrates the SOI substrate and separates the protection circuit.

[0075] According to yet another embodiment of the present technology, there is provided an ultrasonic imaging system including

[0076] a hand-held instrument that has an ultrasonic imaging function and is used in laparoscopic surgery.

[0077] This hand-held instrument having the ultrasonic imaging function includes a semiconductor device including an integrated circuit formed on an SOI substrate including

[0078] a silicon substrate formed of crystalline silicon,

[0079] a BOX layer laminated on the silicon substrate, and

[0080] an SOI layer laminated on the BOX layer, the semiconductor device including

[0081] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and

[0082] an element separation region that penetrates the SOI substrate and separates the protection circuit.

[0083] According to yet another embodiment of the present technology, there is provided an ultrasonic imaging system including

[0084] robotic forceps that have an ultrasonic imaging function and are used in laparoscopic surgery

[0085] These robotic forceps having the ultrasonic imaging function include a semiconductor device including an integrated circuit formed on an SOI substrate including

[0086] a silicon substrate formed of crystalline silicon,

[0087] a BOX layer laminated on the silicon substrate, and

[0088] an SOI layer laminated on the BOX layer, the semiconductor device including

[0089] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and

[0090] an element separation region that penetrates the SOI substrate and separates the protection circuit.

Advantageous Effects of Invention

[0091] As described hereinabove, according to the present technology, a semiconductor device including a protection circuit that exhibits satisfactory performance even in a small area, an ultrasonic image pickup device, a semiconductor device manufacturing method, and an ultrasonic imaging system can be provided. Note that, the advantages disclosed herein are not necessarily limited to those described hereinabove, and all of the advantages disclosed herein can be obtained.

BRIEF DESCRIPTION OF DRAWINGS

[0092] FIG. 1 A cross-sectional view of a semiconductor device according to a first embodiment of the present technology.

[0093] FIG. 2 A cross-sectional view of a part of a configuration of the semiconductor device.

[0094] FIG. 3 A cross-sectional view of an SOI substrate that is used for preparing the semiconductor device.

[0095] FIG. 4 A plan view of an element separation region of the semiconductor device.

[0096] FIG. 5 A schematic diagram of an impedance matching circuit that utilizes the semiconductor device.

[0097] FIG. 6 A schematic view illustrating a manufacturing method for the semiconductor device.

[0098] FIG. 7 Another schematic view illustrating the manufacturing method for the semiconductor device.

[0099] FIG. 8 Still another schematic view illustrating the manufacturing method for the semiconductor device.

[0100] FIG. 9 Yet another schematic view illustrating the manufacturing method for the semiconductor device.

[0101] FIG. 10 Yet another schematic view illustrating the manufacturing method for the semiconductor device.

[0102] FIG. 11 A schematic view illustrating another manufacturing method for the semiconductor device.

[0103] FIG. 12 Another schematic view illustrating the other manufacturing method for the semiconductor device.

[0104] FIG. 13 A cross-sectional view of a semiconductor device according to a first modification of the first embodiment.

[0105] FIG. 14 A cross-sectional view of a semiconductor device according to a second modification of the first embodiment.

[0106] FIG. 15 A schematic view of an IVUS (intravascular ultrasound endoscope) that utilizes the semiconductor devices according to the present technology.

[0107] FIG. 16 A schematic view of an IVUS having a general structure.

[0108] FIG. 17 A cross-sectional view of a semiconductor device according to a second embodiment of the present technology.

[0109] FIG. 18 A cross-sectional view of a part of a configuration of the semiconductor device.

[0110] FIG. 19 A schematic diagram of an impedance matching circuit that utilizes the semiconductor device.

[0111] FIG. 20 A schematic view of an intraoperative ultrasonic probe that utilizes the semiconductor devices according to the present technology.

[0112] FIG. 21 A schematic view of an intraoperative ultrasonic probe having a general structure.

[0113] FIG. 22 A schematic view of a laparoscopic surgical holder that utilizes the semiconductor devices according to the present technology.

[0114] FIG. 23 A schematic view of a laparoscopic surgical holder having a general structure.

[0115] FIG. 24 A schematic view of a handle portion of a laparoscopic surgical holder that utilizes the semiconductor devices according to the present technology.

[0116] FIG. 25 A schematic view of robotic forceps of a laparoscopic-surgery surgical robot that utilizes the semiconductor devices according to the technology.

[0117] FIG. 26 A schematic view of robotic forceps of a laparoscopic-surgery surgical robot having a general structure.

MODES FOR CARRYING OUT THE INVENTION

First Embodiment

[0118] A semiconductor device according to a first embodiment of the present technology is described.

Configuration of Semiconductor Device

[0119] FIG. 1 is a cross-sectional view of a configuration of a semiconductor device 100 according to this embodiment, and FIG. 2 is a cross-sectional view of a part of the configuration of the semiconductor device 100. As illustrated in these drawings, the semiconductor device 100 includes an LV (Low Voltage) circuit 110, a first diode 130, a second diode 150, a silicon substrate 171, a BOX (buried oxide: buried oxide film) layer 172, an element separation region 173, a bottom-surface insulating layer 174, a ground electrode 175, and a top-surface insulating layer 176.

[0120] The semiconductor device 100 is an integrated circuit including the LV circuit 110, the first diode 130, and the second diode 150. The first diode 130 and the second diode 150 serve as protection circuits of this integrated circuit.

[0121] The semiconductor device 100 can be prepared from a single SOI substrate. FIG. 3 is a schematic view of an SOI substrate 200 of the semiconductor device 100. As illustrated in FIG. 3, the SOI substrate 200 includes a silicon substrate 201, a BOX layer 202, and an SOI layer 203.

[0122] The silicon substrate 201 is made of P-type crystalline silicon. The BOX layer 202, which is made of SiO₂, is laminated on the BOX layer 202. The SOI layer 203, which is made of silicon, is laminated on the BOX layer 202. The SOI substrate 200 can be prepared by a SIMOX (Separation by IMplantation of OXygen) method or by a bonding method.

[0123] The semiconductor device 100 is prepared by executing a processing process described below on the SOI substrate 200. The silicon substrate 171 of the semiconductor device 100 corresponds to a part of the silicon substrate 201 of the SOI substrate 200, and the BOX layer 172 of the semiconductor device 100 corresponds to a part of the BOX layer 202 of the SOI substrate 200.

[0124] In the following, among parts that are formed by processing the SOI substrate 200 of the semiconductor device 100 (structure of FIG. 2), a surface on the LV circuit 110 side is referred to as a top surface 100a, and a surface on a side opposite thereto is referred to as a bottom surface 100b.

[0125] The LV circuit 110 includes an N-type semiconductor region 111, a P-type semiconductor region 112, N⁺⁺-type semiconductor regions 113, P⁺⁺-type semiconductor regions 114, a first gate electrode 115, a second gate electrode 116, gate insulating films 117, an element separation layer 118, and signal wires 119.

[0126] The N-type semiconductor region 111, which is made of silicon doped with an N-type dopant, is laminated on the BOX layer 172. A typical N-type dopant is phosphorus. The P-type semiconductor region 112, which is made of silicon doped with a P-type dopant, is laminated on the BOX layer 172. A typical P-type dopant is boron. The N-type semiconductor region 111 and the P-type semiconductor

region 112 are exposed on the top surface 100a, and are separated from each other by the element separation layer 118 made of SiO₂.

[0127] The N⁺⁺-type semiconductor regions 113 are made of silicon doped with a large amount of the N-type dopant, and are formed apart from each other at two positions in the P-type semiconductor region 112. The N⁺⁺-type semiconductor regions 113 are exposed on the top surface 100a, and are connected to the signal wires 119.

[0128] The P⁺⁺-type semiconductor regions 114 are made of silicon doped with a large amount of the P-type dopant, and are formed apart from each other at two positions in the N-type semiconductor region 111. The P⁺⁺-type semiconductor regions 114 are exposed on the top surface 100a, and are connected to the signal wires 119.

[0129] The first gate electrode 115 is made of metals such as aluminum or conductive materials such as polysilicon, and is formed on the N-type semiconductor region 111 through intermediation of the gate insulating film 117. The second gate electrode 116 is made of the metals such as aluminum or the conductive materials such as polysilicon, and is formed on the P-type semiconductor region 112 through intermediation of the gate insulating film 117.

[0130] The N-type semiconductor region 111, the P-type semiconductor region 112, the N⁺⁺-type semiconductor regions 113, and the P⁺⁺-type semiconductor regions 114 are regions formed by implanting the P-type dopant or the N-type dopant into the SOI layer 203 of the SOI substrate 200. The element separation layer 118 is a region formed by oxidizing the SOI layer 203 into SiO₂.

[0131] Note that, the configuration of the LV circuit 110 is not limited to the above-described configuration as long as the configuration of the LV circuit 110 can be prepared by processing the SOI layer 203 of the SOI substrate 200.

[0132] The first diode 130 includes an N-type semiconductor region 131, a P-type semiconductor region 132, a P⁺⁺-type semiconductor region 133, a ground wire 134, and a signal wire 135. The N-type semiconductor region 131 is made of the silicon doped with the N-type dopant, and the P-type semiconductor region 132 is made of the silicon doped with the P-type dopant. The P⁺⁺-type semiconductor region 133 is made of the silicon doped with the large amount of the P-type dopant. In other words, the N-type semiconductor region 131 is a semiconductor region of a first impurity type (N type), and the P-type semiconductor region 132 and the P⁺⁺-type semiconductor region 133 are each a semiconductor region of a second impurity type (P type).

[0133] The N-type semiconductor region 131 and the P-type semiconductor region 132 are laminated on each other. The N-type semiconductor region 131 is exposed on the bottom surface 100b, and the P-type semiconductor region 132 is exposed on the top surface 100a. The P⁺⁺-type semiconductor region 133 is formed in the P-type semiconductor region 132, and is exposed on the top surface 100a.

[0134] The N-type semiconductor region 131, the P-type semiconductor region 132, and the P⁺⁺-type semiconductor region 133 are each made of the crystalline silicon, and have the same crystal orientation as the silicon substrate 171. This is because these semiconductor regions are each made of the crystalline silicon that is formed by the implantation of the dopants into parts of the silicon substrate 201, or formed by an epitaxial crystal growth method on the silicon substrate 201.

[0135] On the bottom surface **100b**, the ground wire **134** is connected to the N-type semiconductor region **131**. On the top surface **100a**, the signal wire **135** is connected to the P⁺⁺-type semiconductor region **133**.

[0136] The second diode **150** includes a P-type semiconductor region **151**, an N-type semiconductor region **152**, an N⁺⁺-type semiconductor region **153**, a ground wire **154**, and a signal wire **155**. The P-type semiconductor region **151** is made of the silicon doped with the P-type dopant, and the N-type semiconductor region **152** is made of the silicon doped with the N-type dopant. The N⁺⁺-type semiconductor region **153** is made of the silicon doped with the large amount of the N-type dopant. In other words, the P-type semiconductor region **151** is the semiconductor region of the second impurity type (P type), and the N-type semiconductor region **152** and the N⁺⁺-type semiconductor region **153** are each the semiconductor region of the first impurity type (N type).

[0137] The P-type semiconductor region **151** and the N-type semiconductor region **152** are laminated on each other. The P-type semiconductor region **151** is exposed on the bottom surface **100b**, and the N-type semiconductor region **152** is exposed on the top surface **100a**. The N⁺⁺-type semiconductor region **153** is formed in the N-type semiconductor region **152**, and is exposed on the top surface **100a**.

[0138] The P-type semiconductor region **151**, the N-type semiconductor region **152**, and the N⁺⁺-type semiconductor region **153** are each made of the crystalline silicon, and have the same crystal orientation as the silicon substrate **171**. This is because these semiconductor regions are each made of the monocrystalline silicon that is formed by the implantation of the dopants into parts of the silicon substrate **201**, or formed by the epitaxial crystal growth method on the silicon substrate **201**.

[0139] On the bottom surface **100b**, the ground wire **154** is connected to the P-type semiconductor region **151**. On the top surface **100a**, the signal wire **155** is connected to the N⁺⁺-type semiconductor region **153**.

[0140] The element separation region **173** separates the first diode **130** and the second diode **150** from each other. The element separation region **173** penetrates from the top surface **100a** to the bottom surface **100b**. FIG. 4 is a schematic view of the element separation region **173** as viewed from the top surface **100a** side. As illustrated in FIG. 4, the element separation region **173** is formed around the first diode **130** and the second diode **150**.

[0141] The element separation region **173** is made of a material of any one or two or more of silicon oxide, silicon nitride, or polysilicon. For example, the element separation region **173** may have a structure obtained by forming a film of insulating materials such as silicon oxide or silicon nitride in a through-hole formed in the SOI substrate **200**, and by filling the hole with polysilicon.

[0142] The bottom-surface insulating layer **174** is arranged on the bottom surface **100b** so as to prevent diffusion of moisture or impurity. The bottom-surface insulating layer **174** is made of, for example, p-SiO (silicon oxide formed by plasma-enhanced chemical vapor deposition). The bottom-surface insulating layer **174** is patterned such that the N-type semiconductor region **131** and the P-type semiconductor region **151** are exposed, and that the bottom-surface insulating layer **174** has opening portions in which the ground wire **134** and the ground wire **154** are formed.

[0143] The ground electrode **175** is arranged on the bottom-surface insulating layer **174**, and is connected to the ground wire **134** and the ground wire **154**. With this, the ground electrode **175** is electrically conducted to the N-type semiconductor region **131** and the P-type semiconductor region **151**. In this way, the ground electrode **175** forms, cooperatively with the ground wire **134** and the ground wire **154**, a ground contact structure for the first diode **130** and the second diode **150**. The ground electrode **175** is made of the conductive materials such as aluminum.

[0144] The top-surface insulating layer **176** is arranged on the top surface **100a** so as to seal the circuits. The top-surface insulating layer **176** is made of the insulating materials such as SiO₂.

Utilization Example of Semiconductor Device

[0145] FIG. 5 is a schematic diagram of a circuit configuration of an impedance matching circuit **301** of an ultrasonic transducer **300** that is capable of utilizing the semiconductor device **100**.

[0146] As shown in FIG. 5, the impedance matching circuit **301** includes an amplifier **302**, a capacitor **303**, a first TR (transmit-receive) switch **304**, a second TR switch **305**, and a third TR switch **306**. The first TR switch **304**, the second TR switch **305**, and the third TR switch **306** are each a back-to-back diode. The back-to-back diode refers to a pair of diodes arranged, as shown in FIG. 5, in a manner that a P-type semiconductor region of one is connected to an N-type semiconductor region of another.

[0147] A drive signal to the ultrasonic transducer **300** reaches the ultrasonic transducer **300** via the first TR switch **304** and the capacitor **303**, and causes the ultrasonic transducer **300** to generate ultrasonic waves. The second TR switch **305** and the third TR switch **306** prevent the drive signal from reaching the amplifier **302**. Note that, depending on how the transducer needs to be driven, the capacitor **303** may be short-circuited.

[0148] When reflected waves of the ultrasonic waves reach the ultrasonic transducer **300**, the ultrasonic transducer **300** generates a detection signal. The detection signal is amplified by the amplifier **302**, and then output.

[0149] In this way, the impedance matching circuit **301** includes the amplifier **302** being an amplifier circuit, the first TR switch **304**, the second TR switch **305**, and the third TR switch **306** being protection circuits.

[0150] In the semiconductor device **100**, the LV circuit **110** can be utilized as the amplifier **302**, and the first diode **130** and the second diode **150** can be utilized as the TR switch. With this, the impedance matching circuit **301** can be provided in the single semiconductor device **100**.

[0151] Note that, the first diode **130** and the second diode **150** constitute one of the three TR switches. Similar to the first diode **130** and the second diode **150**, other two of the switches can also be formed in the semiconductor device **100**.

[0152] Further, as described above, the first diode **130** and the second diode **150** constitute the back-to-back diode. In a large number of high-voltage elements, the back-to-back diode is used as an element having a function of a Zener diode. When the diodes are unidirectional, wires need to be connected to the diodes from a side surface of a substrate, or through-wires need to be formed and connected thereto. Thus, there are a risk of a decrease in yield and an increase

in cost in proportion to the number of steps, and a risk of degradation in wiring reliability.

[0153] In contrast, in the semiconductor device 100, on the same SOI substrate, the back-to-back diode is constituted by the first diode 130 and the second diode 150, and both the diodes are connected to the common ground electrode 175. With this, wire routing is simplified. As a result, improvement in yield, cost reduction, and enhancement in wiring reliability can be achieved.

[0154] Note that, the impedance matching circuit of the ultrasonic transducer is a utilization example of the semiconductor device 100, and the semiconductor device 100 can be utilized as various circuits that are formed on the SOI substrate and include the protection circuits.

Advantages of Semiconductor Device

[0155] As described above, the semiconductor device 100 is provided by forming the LV circuit 110, the first diode 130, and the second diode 150 on the single SOI substrate. Channel regions without the BOX layer 202 are formed on the SOI substrate 200, and the first diode 130 and the second diode 150 are formed therein. In this way, the first diode 130 and the second diode 150 to serve as the TR switch can be formed. With this, surge charge is easily discharged.

[0156] Further, the element separation region 173 between the first diode 130 and the second diode 150 has a through-trench structure penetrating from the top surface 100a to the bottom surface 100b. With this, “latch-up free,” that is, prevention of latch-up (short-circuiting) can be achieved.

[0157] In addition, the first diode 130 and the second diode 150 are each made of the monocrystalline silicon. With this, satisfactory leakage-current characteristics are secured, and a function of the protection circuit is enhanced. Specifically, polysilicon has a mobility of from 1 to 10 cm²/Vs, and the crystalline silicon has a mobility of from approximately 500 to 1,000 cm²/Vs. In depletion regions, the crystalline silicon has a lower resistance of from approximately 1/100 to 1/500.

[0158] In particular, a resistance of an “i” layer (layer that is located at a boundary between the N-type semiconductor region and the P-type semiconductor region and has a low dopant density) is problematic. In the “i” layer (P: 1×10⁻¹⁴/cm³) having a thickness of 1 μm and an area of 25² μm², a resistance of polysilicon is 998 Ω, and a resistance of the crystalline silicon is 2 Ω. Thus, in a case where a diode that allows a forward current of 2 A at 200 V to flow therethrough is prepared, a polysilicon diode needs to have an area of 6,242 μm², but the crystalline-silicon diode needs to have an area of 12.5 μm².

[0159] Thus, in a case where the diode that is prepared from polysilicon needs to have an area of 80 μm², the diode that is prepared from the crystalline silicon needs to have an area of only 4 μm². Generally, in semiconductor devices including the diodes prepared from polysilicon, the diodes need to be formed with use of a plurality of through-trenches. In contrast, the semiconductor device 100 according to this embodiment only needs to have a single diode of 5×5 μm², and hence an area of implementing the semiconductor device 100 can be reduced.

Manufacturing Method 1 for Semiconductor Device

[0160] A manufacturing method for the semiconductor device 100 is described. As described above, the semiconductor device 100 can be prepared from the SOI substrate 200 (refer to FIG. 3).

[0161] FIG. 6 to FIG. 10 are each a schematic view illustrating the manufacturing method for the semiconductor device 100. As illustrated in (a) of FIG. 6, a sacrificial layer 204 is laminated on the SOI layer 203 of the SOI substrate 200. The sacrificial layer 204 is made of, for example, SiO₂. Then, as illustrated in (b) of FIG. 6, the sacrificial layer 204, the SOI layer 203, and the BOX layer 202 are removed by, for example, etching such that the silicon substrate 201 is exposed.

[0162] Next, as illustrated in (c) of FIG. 6, on the silicon substrate 201, crystalline silicon 205 is grown by the epitaxial crystal growth method. By the epitaxial crystal growth method, the silicon substrate 201 and the crystalline silicon 205 have the same crystal orientation.

[0163] After that, as illustrated in (a) of FIG. 7, the sacrificial layer 204 is laminated on the crystalline silicon 205, and trenches T are formed. The trenches T are formed from the crystalline silicon 205 to the silicon substrate 201, and may each have a depth of approximately several ten μm. By the trenches T, parts of the silicon substrate 201 and the crystalline silicon 205 are separated from each other. With this, a structure A1 and a structure A2 are formed.

[0164] Then, as illustrated in (b) of FIG. 7, a diffusion preventing layer 206 is laminated on the sacrificial layer 204 and in the trenches T, and then patterned such that the structure A1 is exposed. The diffusion preventing layer 206 is made of, for example, silicon nitride.

[0165] Next, as illustrated in (c) of FIG. 7, PSG (Phosphorus Silicon Glass) 207 and BSG (Boron Silicon Glass) 208 are filled in the trenches T. At the time of filling, HDP (High Density Plasma) can be used. Alternatively, thin films of the BSG and the PSG may be formed by HDP, and then the BSG and the PSG may be laminated on each other by CVD.

[0166] After that, solid-phase diffusion is performed such that, as illustrated in (a) of FIG. 8, the structure A1 is doped with the dopants. In the structure A1, phosphorus from the PSG 207 is doped into a region adjacent to the PSG 207. With this, the N-type semiconductor region 131 is formed. In the structure A1, boron from the BSG 208 is doped into a region adjacent to the BSG 208. With this, the P-type semiconductor region 132 is formed. The solid-phase diffusion can be performed by heating.

[0167] Then, as illustrated in (b) of FIG. 8, a diffusion preventing layer 209 is laminated on the sacrificial layer 204 and in an element separation trench T, and then patterned such that the structure A2 is exposed. The diffusion preventing layer 209 is made of, for example, silicon nitride.

[0168] Next, as illustrated in (c) of FIG. 8, BSG 210 and PSG 211 are filled in the trench T. At the time of filling, as described above, HDP, CVD, and the like may be used.

[0169] After that, solid-phase diffusion is performed such that, as illustrated in (a) of FIG. 9, the structure A2 is doped with the dopants. In the structure A2, boron from the BSG 210 is doped into a region adjacent to the BSG 210. With this, the P-type semiconductor region 151 is formed. In the structure A2, phosphorus from the PSG 211 is doped into a region adjacent to the PSG 211. With this, the N-type semiconductor region 152 is formed. The solid-phase diffusion can be performed by heating.

[0170] Then, as illustrated in (b) of FIG. 9, the element separation region 173 is formed. The element separation region 173 can be formed by filling the material of any one or two or more of silicon oxide, silicon nitride, or polysilicon

into the trench T. For example, the element separation region 173 can be formed by forming a film of the insulating materials such as silicon nitride or silicon nitride in the trench T, and then by filling polysilicon into the trench T.

[0171] Generally, HDP is used at the time of forming the element separation region 173. However, not only, for example, the PSG and BPSG (Boron Phosphorus Silicon Glass), but also oxide films of, for example, PSG/BPSG, which have high coverage, may be formed by CVD and used in combination therewith. Alternatively, there may be used a combination of HDP and polysilicon, which is widely used in the related art in high-voltage processes for, for example, IGBTs (Insulated Gate Bipolar Transistors).

[0172] Next, as illustrated in (c) of FIG. 9, the N-type semiconductor region 111, the P-type semiconductor region 112, the N⁺⁺-type semiconductor regions 113, the P⁺⁺-type semiconductor regions 114, the P⁺⁺-type semiconductor region 133, and the N⁺⁺-type semiconductor region 153 are formed. These can be formed by doping the N-type dopant and the P-type dopant into the SOI layer 203, the P-type semiconductor region 132, and the N-type semiconductor region 152. A method of doping is not particularly limited, and, for example, ion implantation or the solid-phase diffusion may be utilized. Further, as illustrated in (c) of FIG. 9, a part of the SOI layer 203 is oxidized to form the element separation layer 118.

[0173] After that, as illustrated in (a) of FIG. 10, the signal wire 135, the signal wire 155, the signal wires 119, the gate insulating films 117, the first gate electrode 115, and the second gate electrode 116 are formed. The gate insulating films 117 can be formed by the oxidization of the SOI layer 203. The signal wire 135, the signal wire 155, the signal wires 119, the first gate electrode 115, and the second gate electrode 116 can be formed by, for example, formation of films of the conductive materials through CVD.

[0174] Then, as illustrated in (b) of FIG. 10, the top-surface insulating layer 176 is formed. The top-surface insulating layer 176 can be formed by, for example, CVD. Next, as illustrated in (c) of FIG. 10, a rear surface of the silicon substrate 201 is polished. The polishing is continued until the N-type semiconductor region 131 and the P-type semiconductor region 151 are exposed.

[0175] Next, the bottom-surface insulating layer 174, the ground wire 134, the ground wire 154, and the ground electrode 175 are formed (refer to FIG. 1). In order to form the bottom-surface insulating layer 174, a film of TEOS (Tetraethyl orthosilicate) is formed by the plasma-enhanced chemical vapor deposition, and then patterned. TEOS is transformed into SiO₂ by heating. The ground wire 134, the ground wire 154, and the ground electrode 175 can be formed by various metalization processes such as CVD.

[0176] The semiconductor device 100 can be prepared in this way. As described hereinabove, a part of the silicon substrate 201 of the SOI substrate 200 serves as the silicon substrate 171 of the semiconductor device 100, and a part of the BOX layer 202 of the SOI substrate 200 serves as the BOX layer 172 of the semiconductor device 100.

Manufacturing Method 2 for Semiconductor Device

[0177] The semiconductor device 100 may be prepared as follows.

[0178] FIG. 11 and FIG. 12 are each a schematic view illustrating another manufacturing method for the semiconductor device 100. As illustrated in (a) of FIG. 11, the

sacrificial layer 204 is laminated on the SOI layer 203 of the SOI substrate 200. The sacrificial layer 204 is made of, for example, SiO₂.

[0179] Then, as illustrated in (b) of FIG. 11, the sacrificial layer 204, the SOI layer 203, the BOX layer 202, and a part of the silicon substrate 201 are removed by, for example, etching such that the silicon substrate 201 is exposed.

[0180] Then, as illustrated in (c) of FIG. 11, an N-type semiconductor region 212 and a P-type semiconductor region 213 are formed. These can be formed by doping the N-type dopant and the P-type dopant into the silicon substrate 201 through the ion implantation or the solid-phase diffusion.

[0181] Next, as illustrated in (a) of FIG. 12, crystalline silicon 214 is grown by the epitaxial crystal growth method. At the same time, the dopants are doped by the ion implantation or the solid-phase diffusion so as to form the N-type semiconductor region 212 and the P-type semiconductor region 213. The growth of the crystalline silicon 214 and the doping of the dopants are continued until the N-type semiconductor region 212 and the P-type semiconductor region 213 each have a certain thickness.

[0182] After that, as illustrated in (b) of FIG. 12, the crystalline silicon 214 is grown by the epitaxial crystal growth method. At the same time, a P-type semiconductor region 215 and an N-type semiconductor region 216 are formed. The P-type semiconductor region 215 is formed on the N-type semiconductor region 212, and the N-type semiconductor region 216 is formed on the P-type semiconductor region 213. The P-type semiconductor region 215 and the N-type semiconductor region 216 can be formed by doping the dopants through the ion implantation or the solid-phase diffusion. The growth of the crystalline silicon 214 and the doping of the dopants are continued until the P-type semiconductor region 215 and the N-type semiconductor region 216 each have a certain thickness.

[0183] (c) of FIG. 12 illustrates a state in which the growth of the crystalline silicon 214 and the doping of the dopants have been completed. The N-type semiconductor region 212 corresponds to the N-type semiconductor region 131 of the first diode 130 (refer to FIG. 2), and the P-type semiconductor region 213 corresponds to the P-type semiconductor region 151 of the second diode 150, respectively. Further, the P-type semiconductor region 215 corresponds to the P-type semiconductor region 132 of the first diode 130, and the N-type semiconductor region 216 corresponds to the N-type semiconductor region 152 of the second diode 150, respectively.

[0184] Then, the silicon substrate 201 is oxidized around the first diode 130 and the second diode 150 such that silicon oxide is formed. With this, the element separation region 173 is formed as in (b) of FIG. 9. Subsequently, as in the above-described manufacturing method, the LV circuit 110 and the wires are formed. In this way, the semiconductor device 100 can be prepared.

[0185] Note that, the manufacturing methods for the semiconductor device 100 are not limited to those described above as long as the semiconductor device 100 can be manufactured from the SOI substrate 200.

Modification

[0186] FIG. 13 is a cross-sectional view of a configuration of a semiconductor device 400 according to a first modification of the present technology. As illustrated in FIG. 13,

the semiconductor device **400** includes a ground wire **401**. Other configuration features of the semiconductor device **400** are the same as those of the semiconductor device **100**. [0187] As illustrated in FIG. 13, the ground wire **401** is connected to both the N-type semiconductor region **131** of the first diode **130** and the P-type semiconductor region **151** of the second diode **150**, and to the ground electrode **175**. Ground potentials of the two diodes constituting the back-to-back diode as shown in FIG. 5 are equal to each other. Thus, the ground wire **401** can be used as a common ground wire for the first diode **130** and the second diode **150**. With this, a width of the element separation region **173** is reduced, and hence an area of the semiconductor device **400** can be reduced in accordance therewith.

[0188] FIG. 14 is a cross-sectional view of a configuration of a semiconductor device **500** according to a second modification of the present technology. As illustrated in FIG. 14, the semiconductor device **500** includes a ground wire **501** and a signal wire **502**. Other configuration features of the semiconductor device **500** are the same as those of the semiconductor device **100**.

[0189] As illustrated in FIG. 14, the ground wire **501** is connected to both the N-type semiconductor region **131** of the first diode **130** and the P-type semiconductor region **151** of the second diode **150**, and to the ground electrode **175**. Further, the signal wire **502** is connected to both the P⁺⁺-type semiconductor region **133** of the first diode **130** and the N⁺⁺-type semiconductor region **153** of the second diode **150**. The potentials of the signal wires of the two diodes constituting the back-to-back diode as shown in FIG. 5 are equal to each other. Thus, the signal wire **502** can be used as a common signal wire for the first diode **130** and the second diode **150**. With this, the width of the element separation region **173** is reduced, and hence an area of the semiconductor device **500** can be reduced in accordance therewith.

Application Example 1

[0190] FIG. 15 is a schematic view of a structure of an IVUS (intravascular ultrasound: intravascular ultrasound endoscope) **600** that is capable of utilizing the semiconductor devices **100** according to this embodiment.

[0191] As illustrated in FIG. 15, the IVUS **600** includes a catheter **601**, an array transducer **602**, and a wire **603**. The array transducer **602** refers to an array of a plurality of ultrasonic transducer modules. The ultrasonic transducer modules each include the ultrasonic transducer **300** and the impedance matching circuit **301** as shown in FIG. 5. As described above, the impedance matching circuit **301** can be provided in the semiconductor device **100**.

[0192] When the drive signal is input to the IVUS **600**, the drive signal is transmitted to the ultrasonic transducers **300** via the impedance matching circuits **301**, and causes the ultrasonic transducers **300** to generate the ultrasonic waves. The generated ultrasonic waves are applied to a vessel wall via the catheter **601** to be inserted into a blood vessel. The reflected waves thereof enter the ultrasonic transducers **300** via the catheter **601**, and then are detected. The detection signals are amplified in the impedance matching circuits **301**, and then transmitted to a control device of the IVUS **600** via the wire **603**.

[0193] FIG. 16 is a schematic view of an IVUS **700** having a general structure. As illustrated in FIG. 16, the IVUS **700** includes a catheter **701**, an array transducer **702**, a signal processing chip **703**, and a wire **704**. The IVUS **700** operates

similar to the IVUS **600**, but the impedance matching circuits are installed in the signal processing chip **703**.

[0194] Generally, in the IVUS, the drive signal is at approximately several ten V, and the detection signals are at approximately several ten μ V. The ultrasonic transducers of the IVUS each have a size as significantly small as approximately several ten μ m, and hence the signals are difficult to output to an outside of the catheter owing to electrical impedance mismatching. Thus, normally, as illustrated in FIG. 16, the signal processing chip including the impedance matching circuits is provided.

[0195] However, the impedance matching circuits are made of silicon, and hence this part is poor in flexibility. As a result, there are difficulties in operating the IVUS. When the semiconductor device **100** according to the present technology is applied, the impedance matching circuits can be integrated with the ultrasonic transducers as illustrated in FIG. 16. With this, the number of inflexible parts is reduced, and hence operability of the IVUS can be increased.

[0196] The semiconductor device **100** is applicable not only to the IVUS but also to general integrated circuits using the SOI substrate. Application of the semiconductor device **100** to low-voltage circuits that may be exposed to ESD (electrostatic discharge) or intentionally-generated high-voltage pulses is likely to be especially advantageous.

Application Example 2

[0197] FIG. 20 is a schematic view of a structure of an intraoperative ultrasonic probe **1000** that is capable of utilizing the semiconductor devices **100** according to this embodiment. The intraoperative ultrasonic probe **1000** includes an acoustic lens **1001**, an array transducer **1002**, and wires **1003**. The array transducer **1002** refers to an array of a plurality of ultrasonic transducer modules. The ultrasonic transducer modules each include the ultrasonic transducer **300** and the semiconductor device **100**. The semiconductor device **100** constitutes the impedance matching circuit **301** as shown in FIG. 5.

[0198] When the drive signal is input to the intraoperative ultrasonic probe **1000**, the drive signal is transmitted to the ultrasonic transducers **300** via the impedance matching circuits, and causes the ultrasonic transducers **300** to generate the ultrasonic waves. The generated ultrasonic waves are applied to a diagnostic target through the acoustic lens **1001**. The reflected waves thereof enter the ultrasonic transducers **300** through the acoustic lens **1001**, and then are detected. The detection signals are amplified in the impedance matching circuits, and then transmitted to a control device of the intraoperative ultrasonic probe **1000** via the wires **1003**.

[0199] FIG. 21 is a schematic view of an intraoperative ultrasonic probe **1100** having a general structure. As illustrated in FIG. 21, the intraoperative ultrasonic probe **1100** includes an acoustic lens **1101**, an array transducer **1102**, and wires **1103**. The array transducer **1102** refers to an array of a plurality of ultrasonic transducer modules. The ultrasonic transducer modules each include the ultrasonic transducer **300**. The intraoperative ultrasonic probe **1100** operates similar to the intraoperative ultrasonic probe **1000**, but the array transducer **1102** does not include the semiconductor devices constituting the impedance matching circuits.

[0200] The intraoperative ultrasonic wave also transmits the signals at several ten V, and receives the signals at least at several ten μ V. The intraoperative ultrasonic probe also

uses the array transducer in general, and hence the ultrasonic transducers thereof each have a size as significantly small as approximately several ten μm . In particular, for ease of operation with forceps, further downsizing of intraoperative ultrasonic probes of a drop-in type has been demanded. Thus, the signals have become more difficult to output to an outside of the intraoperative ultrasonic probe owing to the electrical impedance mismatching.

[0201] By application of the present technology, an area of the amplifier circuit itself is reduced, and hence a pitch between the ultrasonic transducers can be further reduced. With this, despite downsizing of the array transducer 1002 as illustrated in FIG. 20, degradation of probe performance owing to the impedance mismatching can be restrained. Note that, similar advantages can be expected also when the present technology is applied to the ultrasonic endoscope.

Application Example 3

[0202] FIG. 22 is a schematic view of a structure of a laparoscopic surgical holder 1200 that is capable of utilizing the semiconductor devices 100 according to this embodiment. The laparoscopic surgical holder 1200 includes a holding portion 1201, an acoustic lens 1202, an array transducer 1203, and wires 1204. The holding portion 1201 is configured to be capable of holding an object. The array transducer 1203 refers to an array of a plurality of ultrasonic transducer modules installed in the holding portion 1201. The ultrasonic transducer modules each include the ultrasonic transducer 300 and the semiconductor device 100. The semiconductor device 100 constitutes the impedance matching circuit 301 as shown in FIG. 5.

[0203] When the drive signal is input to the laparoscopic surgical holder 1200, the drive signal is transmitted to the ultrasonic transducers 300 via the impedance matching circuits, and causes the ultrasonic transducers 300 to generate the ultrasonic waves. The generated ultrasonic waves are applied to a diagnostic target in contact with the acoustic lens 1202. The reflected waves thereof enter the ultrasonic transducers 300, and then are detected. The detection signals are amplified in the impedance matching circuits, and then transmitted to a control device of the laparoscopic surgical holder 1200 via the wires 1204.

[0204] FIG. 23 is a schematic view of a laparoscopic surgical holder 1300 having a general structure. As illustrated in FIG. 23, the laparoscopic surgical holder 1300 includes a holding portion 1301, an acoustic lens 1302, an array transducer 1303, and wires 1304. The array transducer 1303 refers to an array of a plurality of ultrasonic transducer modules. The ultrasonic transducer modules each include the ultrasonic transducer 300. The laparoscopic surgical holder 1300 operates similar to the laparoscopic surgical holder 1200, but the array transducer 1303 does not include the semiconductor devices constituting the impedance matching circuits.

[0205] FIG. 24 is a schematic view of a structure of a handle portion of a laparoscopic surgical holder 1400 that is capable of utilizing the semiconductor devices 100 according to this embodiment. The laparoscopic surgical holder 1400 includes a handle portion illustrated in FIG. 24 and a holding portion like the laparoscopic surgical holder 1300 illustrated in FIG. 23. The semiconductor devices 100 constituting the impedance matching circuits of the ultrasonic

transducers 300 are installed in the handle portion. The semiconductor devices 100 are connected to the array transducer via a wire 1401.

[0206] A surgical instrument including the laparoscopic surgical holder having a distal end at which the ultrasonic probe is incorporated is enabled to perform intraoperative ultrasonic visualization without unnecessary introduction of ports for intraoperative ultrasonic diagnosis. The distal end of the holder is as significantly small as approximately 2×10 mm, and hence characteristic impedance increases. Thus, characteristics are degraded lower than those of existing intraoperative ultrasonic waves.

[0207] Thus, application of the present technology to such a holder as illustrated in FIG. 22 and FIG. 24 assists in maintaining performance of the ultrasonic probe. In FIG. 22, the semiconductor devices 100 are installed at the distal end of the holder. It is ideal and advantageous to install the semiconductor devices 100 close to the ultrasonic transducers. However, in a case where the ultrasonic transducers are smaller than the semiconductor devices 100 according to the present technology, the semiconductor devices 100 may be installed in the handle portion of the holder as illustrated in FIG. 24.

Application Example 4

[0208] FIG. 25 is a schematic view of a structure of robotic forceps of a laparoscopic-surgery surgical robot 1500 that is capable of utilizing the semiconductor devices 100 according to this embodiment. The laparoscopic-surgery surgical robot 1500 includes a holding portion 1501, an acoustic lens 1502, an array transducer 1503, and a wire 1504. The array transducer 1503 refers to an array of a plurality of ultrasonic transducer modules. The ultrasonic transducer modules each include the ultrasonic transducer 300 and the semiconductor device 100. The semiconductor device 100 constitutes the impedance matching circuit 301 as shown in FIG. 5.

[0209] When the drive signal is input to the holding portion 1501, the drive signal is transmitted to the ultrasonic transducers 300 via the impedance matching circuits, and causes the ultrasonic transducers 300 to generate the ultrasonic waves. The generated ultrasonic waves are applied to a diagnostic target in contact with the acoustic lens 1502. The reflected waves thereof enter the ultrasonic transducers 300, and then are detected. The detection signals are amplified in the impedance matching circuits, and then transmitted to a control device of the laparoscopic-surgery surgical robot 1500 via the wire 1504.

[0210] FIG. 26 is a schematic view of a structure of robotic forceps of a laparoscopic-surgery surgical robot 1600 having a general structure. As illustrated in FIG. 26, the laparoscopic-surgery surgical robot 1600 includes a holding portion 1601, an acoustic lens 1602, an array transducer 1603, and a wire 1604. The array transducer 1603 refers to an array of a plurality of ultrasonic transducer modules. The ultrasonic transducer modules each include the ultrasonic transducer 300. The laparoscopic-surgery surgical robot 1600 operates similar to the laparoscopic-surgery surgical robot 1500, but the array transducer 1603 does not include the semiconductor devices constituting the impedance matching circuits.

[0211] A surgical instrument, that is, the robotic forceps of the laparoscopic-surgery surgical robot, which have a distal end at which the ultrasonic probe is incorporated, is enabled

to perform the intraoperative ultrasonic visualization without unnecessary introduction of ports for intraoperative ultrasonic diagnosis. The distal end of the holder is as significantly small as approximately 2×10 mm, and hence characteristic impedance increases. Thus, characteristics are degraded lower than those of the existing intraoperative ultrasonic waves. Thus, application of the present technology to such a holder as illustrated in FIG. 25 assists in maintaining performance of the ultrasonic probe.

[0212] As described hereinabove, the semiconductor devices 100 can be utilized in thin and small medical devices such as an intraoperative ultrasonic image pickup device, an ultrasonic catheter, and the ultrasound endoscope. Further, the semiconductor devices 100 can be utilized also in, for example, geodesic ultrasonography and a geodesic ultrasonic sensor, power circuits of millimeter-wave sensors, and control circuits of LEDs (light emitting diodes) for automobiles or projectors, and utilized for, for example, downsizing and implementation of circuits for telecommunications/modems at 48 V/24 V/12 V, downsizing of small-mechatronics control circuits of, for example, a small robot or an endoscope, downsizing of full-digital audio amplifier circuits, and for downsizing of control circuits of HEMSs (home energy management systems).

[0213] The utilization of the semiconductor devices 100 enables downsizing of integrated circuits, thereby achieving device downsizing, packaging with amplifier circuits, thereby increasing an SNR (signal-noise ratio), downsizing of solid portions including semiconductor chips, thereby increasing operability of, for example, catheters and endoscopes, and downsizing of the semiconductor chips, thereby increasing yield and theoretical yield. As a result, manufacturing cost can be reduced.

Second Embodiment

[0214] A semiconductor device according to a second embodiment of the present technology is described.

Configuration of Semiconductor Device

[0215] FIG. 17 is a cross-sectional view of a configuration of a semiconductor device 800 according to this embodiment, and FIG. 18 is a cross-sectional view of a part of the configuration of the semiconductor device 800. As illustrated in these drawings, the semiconductor device 800 includes an LV (Low Voltage) circuit 810, a first transistor 830, a second transistor 850, a silicon substrate 871, a BOX layer 872, an element separation region 873, a bottom-surface insulating layer 874, a ground electrode 875, and a top-surface insulating layer 876.

[0216] The semiconductor device 800 is an integrated circuit including the LV circuit 810, the first transistor 830, and the second transistor 850. The first transistor 830 and the second transistor 850 serve as protection circuits of this integrated circuit.

[0217] As in the first embodiment, the semiconductor device 800 can be prepared from the single SOI substrate 200 (refer to FIG. 3). The silicon substrate 871 of the semiconductor device 800 corresponds to a part of the silicon substrate 201 of the SOI substrate 200, and the BOX layer 872 of the semiconductor device 800 corresponds to a part of the BOX layer 202 of the SOI substrate 200.

[0218] In the following, among parts that are formed by processing the SOI substrate 200 of the semiconductor

device 800 (structure of FIG. 18), a surface on the LV circuit 810 side is referred to as a top surface 800a, and a surface on a side opposite thereto is referred to as a bottom surface 800b.

[0219] The LV circuit 810 includes an N-type semiconductor region 811, a P-type semiconductor region 812, N⁺⁺-type semiconductor regions 813, P⁺⁺-type semiconductor regions 814, a first gate electrode 815, a second gate electrode 816, gate insulating films 817, an element separation layer 818, and signal wires 819.

[0220] The N-type semiconductor region 811, which is made of the silicon doped with the N-type dopant, is laminated on the BOX layer 872. A typical N-type dopant is phosphorus. The P-type semiconductor region 812, which is made of the silicon doped with the P-type dopant, is laminated on the BOX layer 872. A typical P-type dopant is boron. The N-type semiconductor region 811 and the P-type semiconductor region 812 are exposed on the top surface 800a, and are separated from each other by the element separation layer 818 made of SiO₂.

[0221] The N⁺⁺-type semiconductor regions 813 are made of the silicon doped with the large amount of the N-type dopant, and are formed apart from each other at two positions in the P-type semiconductor region 812. The N⁺⁺-type semiconductor regions 813 are exposed on the top surface 800a, and are connected to the signal wires 819.

[0222] The P⁺⁺-type semiconductor regions 814 are made of the silicon doped with the large amount of the P-type dopant, and are formed apart from each other at two positions in the N-type semiconductor region 811. The P⁺⁺-type semiconductor regions 814 are exposed on the top surface 800a, and are connected to the signal wires 819.

[0223] The first gate electrode 815 is made of the metals such as aluminum or the conductive materials such as polysilicon, and is formed on the N-type semiconductor region 811 through intermediation of the gate insulating film 817. The second gate electrode 816 is made of the metals such as aluminum or the conductive materials such as polysilicon, and is formed on the P-type semiconductor region 812 through intermediation of the gate insulating film 817.

[0224] The N-type semiconductor region 811, the P-type semiconductor region 812, the N⁺⁺-type semiconductor regions 813, and the P⁺⁺-type semiconductor regions 814 are regions formed by implanting the P-type dopant or the N-type dopant into the SOI layer 203 of the SOI substrate 200. The element separation layer 818 is a region formed by oxidizing the SOI layer 203 into SiO₂.

[0225] Note that, the configuration of the LV circuit 810 is not limited to the above-described configuration as long as the configuration of the LV circuit 810 can be prepared by processing the SOI layer 203 of the SOI substrate 200.

[0226] The first transistor 830 is a vertical transistor including a first P-type semiconductor region 831, an N⁻-type semiconductor region 832, a second P-type semiconductor region 833, a P⁺⁺-type semiconductor region 834, a gate electrode 835, a ground wire 836, and a signal wire 837. The first P-type semiconductor region 831 and the second P-type semiconductor region 833 are each made of the silicon doped with the P-type dopant, and the N⁻-type semiconductor region 832 is made of silicon doped with a small amount of the N-type dopant. The P⁺⁺-type semiconductor region 834 is made of the silicon doped with the large amount of the P-type dopant.

[0227] The first P-type semiconductor region **831**, the N⁻-type semiconductor region **832**, and the second P-type semiconductor region **833** are laminated in this order. The first P-type semiconductor region **831** is exposed on the bottom surface **800b**, and the second P-type semiconductor region **833** is exposed on the top surface **800a**. The P⁺⁺-type semiconductor region **834** is formed in the second P-type semiconductor region **833**, and is exposed on the top surface **800a**.

[0228] The first P-type semiconductor region **831**, the N⁻-type semiconductor region **832**, the second P-type semiconductor region **833**, and the P⁺⁺-type semiconductor region **834** are each made of the crystalline silicon, and have the same crystal orientation as the silicon substrate **871**. This is because these semiconductor regions are each made of the crystalline silicon that is formed by the implantation of the dopants into parts of the silicon substrate **201**, or formed by the epitaxial crystal growth method on the silicon substrate **201**.

[0229] The gate electrode **835** is embedded in the element separation region **873**, and functions as a gate electrode of the first transistor **830**. The gate electrode **835** is made of polysilicon. The element separation region **873** may have the structure obtained by forming the film of the insulating materials such as silicon oxide or silicon nitride in a through-hole formed in the SOI substrate **200**, and by filling the hole with polysilicon. This polysilicon can be utilized as the gate electrode **835**.

[0230] On the bottom surface **800b**, the ground wire **836** is connected to the first P-type semiconductor region **831**. On the top surface **800a**, the signal wire **837** is connected to the P⁺⁺-type semiconductor region **834**.

[0231] The second transistor **850** is a vertical transistor including a P-type semiconductor region **851**, an N-type semiconductor region **852**, an N⁺⁺-type semiconductor region **853**, a gate electrode **854**, a ground wire **855**, and a signal wire **856**. The P-type semiconductor region **851** is made of the silicon doped with the P-type dopant, and the N-type semiconductor region **852** is made of the silicon doped with the N-type dopant. The N⁺⁺-type semiconductor region **853** is made of the silicon doped with the large amount of the N-type dopant.

[0232] The P-type semiconductor region **851** and the N-type semiconductor region **852** are laminated on each other. The P-type semiconductor region **851** is exposed on the bottom surface **800b**, and the N-type semiconductor region **852** is exposed on the top surface **800a**. The N⁺⁺-type semiconductor region **853** is formed in the N-type semiconductor region **852**, and is exposed on the top surface **800a**.

[0233] The P-type semiconductor region **851**, the N-type semiconductor region **852**, and the N⁺⁺-type semiconductor region **853** are each made of the crystalline silicon, and have the same crystal orientation as the silicon substrate **201**. This is because these semiconductor regions are each made of the crystalline silicon that is formed by the implantation of the dopants into the parts of the silicon substrate **201**, or formed by the epitaxial crystal growth method on the silicon substrate **201**.

[0234] The gate electrode **854** is embedded in the element separation region **873**, and functions as a gate electrode of the second transistor **850**. The gate electrode **854** is made of polysilicon. The element separation region **873** may have the structure obtained by forming the film of the insulating materials such as silicon oxide or silicon nitride in the

through-hole formed in the SOI substrate **200**, and by filling the hole with polysilicon. This polysilicon can be utilized as the gate electrode **854**.

[0235] On the bottom surface **800b**, the ground wire **855** is connected to the P-type semiconductor region **851**. On the top surface **800a**, the signal wire **856** is connected to the N⁺⁺-type semiconductor region **853**.

[0236] The element separation region **873** separates the first transistor **830** and the second transistor **850** from each other. The element separation region **873** penetrates from the top surface **800a** to the bottom surface **800b**. As in the first embodiment, the element separation region **873** is formed around the first transistor **830** and the second transistor **850** (refer to FIG. 4).

[0237] The element separation region **873** is made of the material of any one or two or more of silicon oxide, silicon nitride, or polysilicon. For example, the element separation region **873** may have the structure obtained by forming the film of the insulating materials such as silicon oxide or silicon nitride in the through-hole formed in the SOI substrate **200**, and by filling the hole with polysilicon. As described above, the polysilicon can be utilized as the gate electrode **835** and the gate electrode **854**.

[0238] The bottom-surface insulating layer **874** is arranged on the bottom surface **800b** so as to prevent diffusion of moisture or impurity. The bottom-surface insulating layer **874** is made of, for example, p-SiO (silicon oxide formed by plasma-enhanced chemical vapor deposition). The bottom-surface insulating layer **874** is patterned such that the first P-type semiconductor region **831** and the P-type semiconductor region **851** are exposed, and that the bottom-surface insulating layer **174** has opening portions in which the ground wire **836** and the ground wire **855** are formed.

[0239] The ground electrode **875** is arranged on the bottom-surface insulating layer **874**, and is connected to the ground wire **836** and the ground wire **855**. With this, the ground electrode **875** is electrically conducted to the first P-type semiconductor region **831** and the P-type semiconductor region **851**. In this way, the ground electrode **875** forms, cooperatively with the ground wire **836** and the ground wire **855**, a ground contact structure for the first transistor **830** and the second transistor **850**. The ground electrode **875** is made of the conductive materials such as aluminum.

[0240] The top-surface insulating layer **876** is arranged on the top surface **800a** so as to seal the circuits. The top-surface insulating layer **876** is made of the insulating materials such as SiO₂.

Utilization Example of Semiconductor Device

[0241] FIG. 5 is a schematic diagram of a circuit configuration of an impedance matching circuit **901** of an ultrasonic transducer **900** that is capable of utilizing the semiconductor device **100**.

[0242] As shown in FIG. 19, the impedance matching circuit **901** includes an amplifier **902**, a first TR (transmit-receive) switch **903**, and a second TR switch **904**.

[0243] When a drive signal to the ultrasonic transducer **900** is input with the first TR switch **903** and the second TR switch **904** being turned OFF, the drive signal reaches the ultrasonic transducer **900**, and causes the ultrasonic transducer **900** to generate ultrasonic waves. The first TR switch

903 and the second TR switch **904** prevent the drive signal from reaching the amplifier **902**.

[0244] The first TR switch **903** and the second TR switch **904** are switched ON immediately after the drive signal reaches the ultrasonic transducer **900**. When reflected waves of the ultrasonic waves reach the ultrasonic transducer **900**, the ultrasonic transducer **900** generates a detection signal. The detection signal reaches the amplifier **902** via the first TR switch **903**, is amplified by the amplifier **902**, and then output via the second TR switch **904**.

[0245] In this way, the impedance matching circuit **901** includes the amplifier **902** being an amplifier circuit, the first TR switch **903** and the second TR switch **904** being protection circuits.

[0246] In the semiconductor device **800**, the LV circuit **810** can be utilized as the amplifier **902**, the first transistor **830** can be utilized as the first TR switch **903**, and the second transistor **850** can be utilized as the second TR switch **904**. With this, the impedance matching circuit **901** can be provided in the single semiconductor device **800**.

[0247] Note that, the impedance matching circuit of the ultrasonic transducer is a utilization example of the semiconductor device **800**, and the semiconductor device **800** can be utilized as various circuits that include the amplifier circuit and the protection circuits.

Advantages of Semiconductor Device

[0248] As described above, the semiconductor device **800** is provided by forming the LV circuit **810**, the first transistor **830**, and the second transistor **850** on the single SOI substrate. Channel regions without the BOX layer **202** are formed on the SOI substrate **200**, and the first transistor **830** and the second transistor **850** are formed therein. In this way, the first transistor **830** and the second transistor **850** to serve as the TR switches can be formed. With this, surge charge is easily discharged.

[0249] Further, the element separation region **873** between the first transistor **830** and the second transistor **850** has a through-trench structure penetrating from the top surface **800a** to the bottom surface **800b**. With this, the “latch-up free” can be achieved.

[0250] In addition, the first transistor **830** and the second transistor **850** are each made of the monocrystalline silicon. As in the first embodiment, satisfactory leakage-current characteristics can be secured, the function of the protection circuit can be enhanced, and the area of implementation can be reduced.

Manufacturing Method for Semiconductor Device

[0251] A manufacturing method for the semiconductor device **800** is described. As described above, the semiconductor device **800** can be prepared from the SOI substrate **200** (refer to FIG. 3), and can be manufactured similar to the semiconductor device **100** according to the first embodiment.

[0252] The gate electrode **835** and the gate electrode **854** can be prepared by, at the time of preparing the element separation region **873**, forming the film of the insulating materials such as silicon nitride or silicon nitride in the trench T (refer to (a) of FIG. 9), filling polysilicon into the trench T, and then routing wires in this polysilicon.

Application Example

[0253] As in the first embodiment, the semiconductor device **800** according to this embodiment can be utilized as the impedance matching circuit of the ultrasonic transducer in the IVUS. The impedance matching circuit can be integrated with the ultrasonic transducer, and hence the operability of the IVUS can be increased. Further, as in the first embodiment, the semiconductor device **800** can be utilized as the impedance matching circuit in various ultrasonic imaging systems including the intraoperative ultrasonic probe, the ultrasound endoscope, the laparoscopic surgical holder, and the laparoscopic-surgery surgical robot.

[0254] As in the first embodiment, the semiconductor device **800** is applicable also to general integrated circuits using the SOI substrate. The utilization of the semiconductor device **800** enables downsizing of integrated circuits, thereby achieving device downsizing, packaging with amplifier circuits, thereby increasing an SNR (signal-noise ratio), downsizing of solid portions including semiconductor chips, thereby increasing operability of, for example, catheters and endoscopes, and downsizing of the semiconductor chips, thereby increasing yield and theoretical yield. As a result, manufacturing cost can be reduced.

[0255] Note that, the present technology may also provide the following configurations.

[0256] (1)

[0257] A semiconductor device including an integrated circuit formed on an SOI substrate including

[0258] a silicon substrate formed of crystalline silicon,

[0259] a BOX (buried oxide) layer laminated on the silicon substrate, and

[0260] an SOI (silicon on insulator) layer laminated on the BOX layer, the semiconductor device including:

[0261] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate; and

[0262] an element separation region that penetrates the SOI substrate and separates the protection circuit.

[0263] (2)

[0264] The semiconductor device according to Item (1), in which the protection circuit is a diode.

[0265] (3)

[0266] The semiconductor device according to Item (1), in which

[0267] the protection circuit is a vertical transistor.

[0268] (4)

[0269] The semiconductor device according to any one of Items (1) to (3), in which

[0270] the element separation region is formed of any one or two or more of silicon oxide, silicon nitride, and polysilicon.

[0271] (5)

[0272] The semiconductor device according to Item (3), in which

[0273] the element separation region includes a gate electrode of the vertical transistor.

[0274] (6)

[0275] The semiconductor device according to any one of Items (1) to (5), in which

[0276] the SOI substrate includes a first surface and a second surface on a side opposite to the first surface,

[0277] the protection circuit includes a first semiconductor element and a second semiconductor element,

- [0278] the first semiconductor element is formed by laminating a first semiconductor region that is on the first surface side and is of a first impurity type, and a second semiconductor region that is on the second surface side and is of a second impurity type, and
- [0279] the second semiconductor element is formed by laminating a third semiconductor region that is on the first surface side and is of the second impurity type, and a fourth semiconductor region that is on the second surface side and is of the first impurity type.
- [0280] (7)
- [0281] The semiconductor device according to Item (6), further including
- [0282] a ground contact structure that is provided on the first surface of the semiconductor device and is electrically conducted to the first semiconductor region and the third semiconductor region.
- [0283] (8)
- [0284] The semiconductor device according to Item (7), in which
- [0285] the ground contact structure includes a ground wire that is connected to the first semiconductor region and the third semiconductor region and is common to both the first semiconductor region and the third semiconductor region.
- [0286] (9)
- [0287] The semiconductor device according to Item (8), in which
- [0288] the ground contact structure includes a ground electrode that is connected to the ground wire and is common to both the first semiconductor region and the third semiconductor region.
- [0289] (10)
- [0290] The semiconductor device according to any one of Items (6) to (9), further including
- [0291] a signal wire that is connected to the second semiconductor region and the fourth semiconductor region, and is common to both the second semiconductor region and the fourth semiconductor region.
- [0292] (11)
- [0293] An ultrasonic image pickup device, including
- [0294] a semiconductor device including an integrated circuit formed on an SOI substrate including
- [0295] a silicon substrate formed of crystalline silicon,
- [0296] a BOX layer laminated on the silicon substrate, and
- [0297] an SOI layer laminated on the BOX layer, the semiconductor device including
- [0298] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
- [0299] an element separation region that penetrates the SOI substrate and separates the protection circuit.
- [0300] (12)
- [0301] A manufacturing method for a semiconductor device including an integrated circuit formed on an SOI substrate, the manufacturing method including:
- [0302] preparing the SOI substrate including
- [0303] a silicon substrate formed of crystalline silicon,
- [0304] a BOX layer laminated on the silicon substrate, and
- [0305] an SOI layer laminated on the BOX layer;
- [0306] forming, by an epitaxial crystal growth method, a protection circuit that configures the integrated circuit and includes a semiconductor region that has the same crystal orientation as the silicon substrate, on the silicon substrate; and
- [0307] forming an element separation region that penetrates the SOI substrate and separates the protection circuit.
- [0308] (13)
- [0309] The manufacturing method for the semiconductor device according to Item (12), in which
- [0310] in the forming of the protection circuit, a substrate polishing method of polishing the silicon substrate from a surface on a side opposite to a surface on a side where crystal growth of the semiconductor region progresses, to expose the semiconductor region, is used.
- [0311] (14)
- [0312] An ultrasonic imaging system, including
- [0313] an ultrasonic catheter including a semiconductor device including an integrated circuit formed on an SOI substrate including
- [0314] a silicon substrate formed of crystalline silicon,
- [0315] a BOX layer laminated on the silicon substrate, and
- [0316] an SOI layer laminated on the BOX layer, the semiconductor device including
- [0317] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
- [0318] an element separation region that penetrates the SOI substrate and separates the protection circuit.
- [0319] (15)
- [0320] An ultrasonic imaging system, including:
- [0321] an intraoperative ultrasonic probe or an ultrasound endoscope including a semiconductor device including an integrated circuit formed on an SOI substrate including
- [0322] a silicon substrate formed of crystalline silicon,
- [0323] a BOX layer laminated on the silicon substrate, and
- [0324] an SOI layer laminated on the BOX layer, the semiconductor device including
- [0325] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
- [0326] an element separation region that penetrates the SOI substrate and separates the protection circuit.
- [0327] (16)
- [0328] An ultrasonic imaging system, including
- [0329] a hand-held instrument that has an ultrasonic imaging function and is used in laparoscopic surgery, the hand-held instrument including a semiconductor device including an integrated circuit formed on an SOI substrate including a silicon substrate formed of crystalline silicon,
- [0330] a BOX layer laminated on the silicon substrate, and
- [0331] an SOI layer laminated on the BOX layer, the semiconductor device including

- [0332] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
- [0333] an element separation region that penetrates the SOI substrate and separates the protection circuit.
- [0334] (17)
- [0335] An ultrasonic imaging system, including
- [0336] robotic forceps that have an ultrasonic imaging function and are used in laparoscopic surgery, the robotic forceps including a semiconductor device including an integrated circuit formed on an SOI substrate including
- [0337] a silicon substrate formed of crystalline silicon,
- [0338] a BOX layer laminated on the silicon substrate, and
- [0339] an SOI layer laminated on the BOX layer, the semiconductor device including
- [0340] a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
- [0341] an element separation region that penetrates the SOI substrate and separates the protection circuit.

REFERENCE SIGNS LIST

- [0342] 100 semiconductor device
- [0343] 110 LV circuit
- [0344] 130 first diode
- [0345] 150 second diode
- [0346] 171 silicon substrate
- [0347] 172 BOX layer
- [0348] 173 element separation region
- [0349] 175 ground electrode
- [0350] 200 SOI substrate
- [0351] 201 silicon substrate
- [0352] 202 BOX layer
- [0353] 203 SOI layer
- [0354] 800 semiconductor device
- [0355] 810 LV circuit
- [0356] 830 first transistor
- [0357] 850 second transistor
- [0358] 871 silicon substrate
- [0359] 872 BOX layer
- [0360] 873 element separation region
- [0361] 875 ground electrode
1. A semiconductor device including an integrated circuit formed on an SOI substrate including
 - a silicon substrate formed of crystalline silicon,
 - a BOX (buried oxide) layer laminated on the silicon substrate, and
 - an SOI (silicon on insulator) layer laminated on the BOX layer, the semiconductor device comprising:
 - a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate; and
 - an element separation region that penetrates the SOI substrate and separates the protection circuit.
 2. The semiconductor device according to claim 1, wherein
 - the protection circuit is a diode.
 3. The semiconductor device according to claim 1, wherein
 - the protection circuit is a vertical transistor.

4. The semiconductor device according to claim 1, wherein
 - the element separation region is formed of any one or two or more of silicon oxide, silicon nitride, and polysilicon.
5. The semiconductor device according to claim 3, wherein
 - the element separation region includes a gate electrode of the vertical transistor.
6. The semiconductor device according to claim 1, wherein
 - the SOI substrate includes a first surface and a second surface on a side opposite to the first surface,
 - the protection circuit includes a first semiconductor element and a second semiconductor element,
 - the first semiconductor element is formed by laminating a first semiconductor region that is on the first surface side and is of a first impurity type, and a second semiconductor region that is on the second surface side and is of a second impurity type, and
 - the second semiconductor element is formed by laminating a third semiconductor region that is on the first surface side and is of the second impurity type, and a fourth semiconductor region that is on the second surface side and is of the first impurity type.
7. The semiconductor device according to claim 6, further comprising
 - a ground contact structure that is provided on the first surface of the semiconductor device and is electrically conducted to the first semiconductor region and the third semiconductor region.
8. The semiconductor device according to claim 7, wherein
 - the ground contact structure includes a ground wire that is connected to the first semiconductor region and the third semiconductor region and is common to both the first semiconductor region and the third semiconductor region.
9. The semiconductor device according to claim 8, wherein
 - the ground contact structure includes a ground electrode that is connected to the ground wire and is common to both the first semiconductor region and the third semiconductor region.
10. The semiconductor device according to claim 6, further comprising
 - a signal wire that is connected to the second semiconductor region and the fourth semiconductor region and is common to both the second semiconductor region and the fourth semiconductor region.
11. An ultrasonic image pickup device, comprising
 - a semiconductor device including an integrated circuit formed on an SOI substrate including
 - a silicon substrate formed of crystalline silicon,
 - a BOX layer laminated on the silicon substrate, and
 - an SOI layer laminated on the BOX layer, the semiconductor device including
 - a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
 - an element separation region that penetrates the SOI substrate and separates the protection circuit.

12. A manufacturing method for a semiconductor device including an integrated circuit formed on an SOI substrate, the manufacturing method comprising:

preparing the SOI substrate including

a silicon substrate formed of crystalline silicon,
a BOX layer laminated on the silicon substrate, and
an SOI layer laminated on the BOX layer;

forming, by an epitaxial crystal growth method, a protection circuit that configures the integrated circuit and includes a semiconductor region that has the same crystal orientation as the silicon substrate, on the silicon substrate; and

forming an element separation region that penetrates the SOI substrate and separates the protection circuit.

13. The manufacturing method for a semiconductor device according to claim **12**, wherein

in the forming of the protection circuit, a substrate polishing method of polishing the silicon substrate from a surface on a side opposite to a surface on a side where crystal growth of the semiconductor region progresses, to expose the semiconductor region, is used.

14. An ultrasonic imaging system, comprising
an ultrasonic catheter including a semiconductor device including an integrated circuit formed on an SOI substrate including

a silicon substrate formed of crystalline silicon,
a BOX layer laminated on the silicon substrate, and
an SOI layer laminated on the BOX layer, the semiconductor device including

a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
an element separation region that penetrates the SOI substrate and separates the protection circuit.

15. An ultrasonic imaging system, comprising:
an intraoperative ultrasonic probe or an ultrasound endoscope including a semiconductor device including an integrated circuit formed on an SOI substrate including

a silicon substrate formed of crystalline silicon,
a BOX layer laminated on the silicon substrate, and
an SOI layer laminated on the BOX layer, the semiconductor device including

a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
an element separation region that penetrates the SOI substrate and separates the protection circuit.

16. An ultrasonic imaging system, comprising
a hand-held instrument that has an ultrasonic imaging function and is used in laparoscopic surgery, the hand-held instrument including a semiconductor device including an integrated circuit formed on an SOI substrate including

a silicon substrate formed of crystalline silicon,
a BOX layer laminated on the silicon substrate, and
an SOI layer laminated on the BOX layer, the semiconductor device including

a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
an element separation region that penetrates the SOI substrate and separates the protection circuit.

17. An ultrasonic imaging system, comprising
robotic forceps that have an ultrasonic imaging function and are used in laparoscopic surgery, the robotic forceps including a semiconductor device including an integrated circuit formed on an SOI substrate including
a silicon substrate formed of crystalline silicon,
a BOX layer laminated on the silicon substrate, and
an SOI layer laminated on the BOX layer, the semiconductor device including

a protection circuit that configures the integrated circuit and includes a semiconductor region having the same crystal orientation as the silicon substrate, and
an element separation region that penetrates the SOI substrate and separates the protection circuit.

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专利名称(译)	半导体器件，超声波图像拾取器件，半导体器件制造方法和超声波成像系统		
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摘要(译)

[目的]提供一种包括即使在小区域中也表现出令人满意的性能的保护电路的半导体器件，超声波图像拾取装置，半导体器件制造方法和超声波成像系统。[解决方案]根据本技术的半导体器件包括形成在SOI衬底上的集成电路，该SOI衬底包括由晶体硅形成的硅衬底，层叠在硅衬底上的BOX层，以及层叠在BOX层上的SOI层，半导体器件包括：保护电路；和元素分离区域。保护电路构成集成电路，并包括具有与硅衬底相同的晶体取向的半导体区域。元件分离区域穿透SOI衬底并分离保护电路。

